

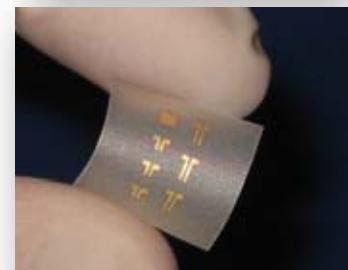
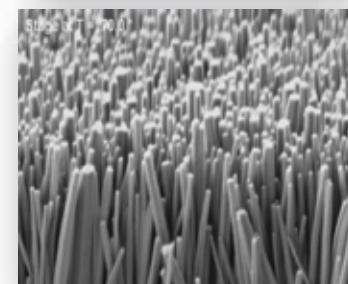
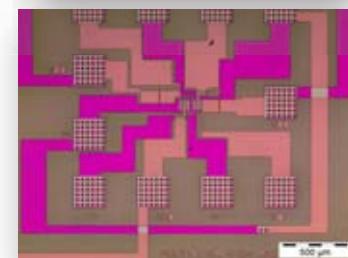
Multifunctional nanoscale oxide conductors and semiconductors

E. Fortunato, L. Pereira, P. Barquinha, R. Martins

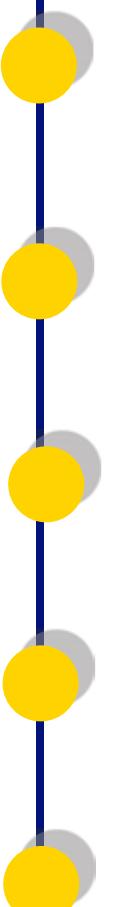
Materials Science Department, CENIMAT/i3N, FCT-UNL, CEMOP/UNINOVA, Portugal

emf@fct.unl.pt

www.cenimat.fct.unl.pt



General Outline



Introduction
Transparent electronics

n-type TFTs by PVD

n-type TFTs by solution

Conclusions

Other applications

Transparent Electronics



Source: YouTube – Samsung's
Transparent Smart Window at
CES 2012 [Official]

...is today a reality!

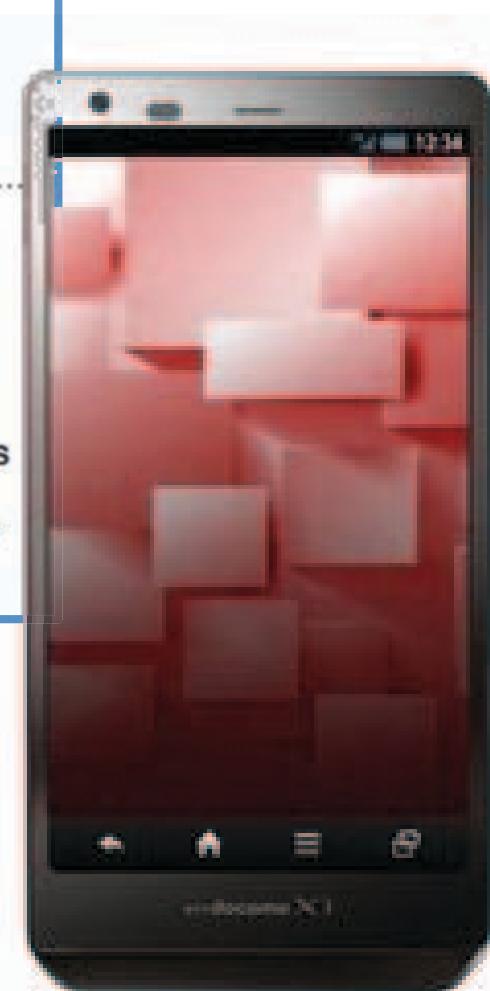
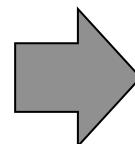


Sharp to Commercialize World's First Small- and Medium-Size LCD Panels using Oxide Semiconductor

Sharp Corporation has developed high performance small- and medium-size LCD panels using oxide semiconductor, InGaZnO (IGZO^{*1}). Production of these new LCD panels will aim to start at Kameyama Plant No.2 within this year.

Meeting the strong demand for small- and medium-size LCD panels used in smart phones and tablet terminals, is accompanied by an increased need for display quality, including high resolution and high picture quality, light weight and compact design, and high energy efficiency.

1st IGZO backplane in market
(4.9", 1280x720, shipping end 2012)



Rumor?!

Oxide TFT

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best of bz

iPad 5 Likely to Use New, Lighter and Thinner Technology (AAPL)

Thursday, July 25, 2013 - 9:08am

[AAPL](#), [Apple](#), [Digitimes](#), [iPad 5](#), [iPad Mini](#), [LPL](#), [News](#), [Oxide TFT](#)

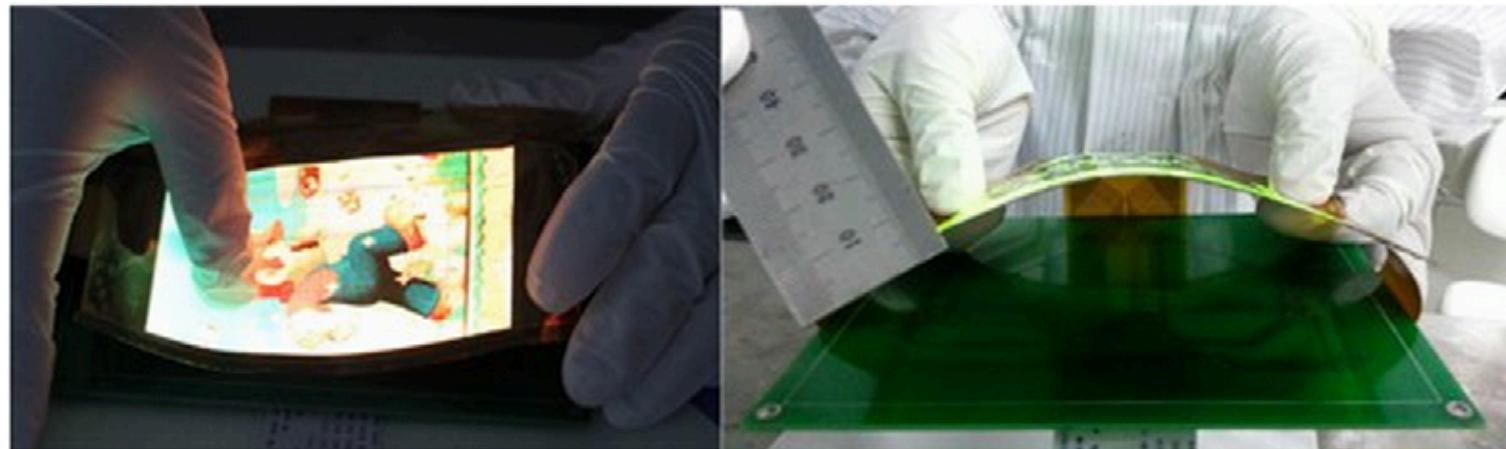


Apple's (NASDAQ: AAPL) long-awaited iPad upgrade is expected to be one of the lightest and thinnest tablets of its kind. According to DigiTimes, the fifth-generation iPad will use GF2 touch screen technology, which will allow Apple to build a lighter and thinner tablet. TPK and GIS will... [Read More >>](#)

Oxide TFT News

Guangzhou New Vision developed an Ln-IZO based 4.8" flexible AMOLED panel

Guangzhou New Vision Optoelectronics (NVO) developed a flexible 4.8" AMOLED display. This full-color panel is only 100 microns thick and weighs just one gram. This panel uses an Ln-IZO backplane and a Polyimide substrate.



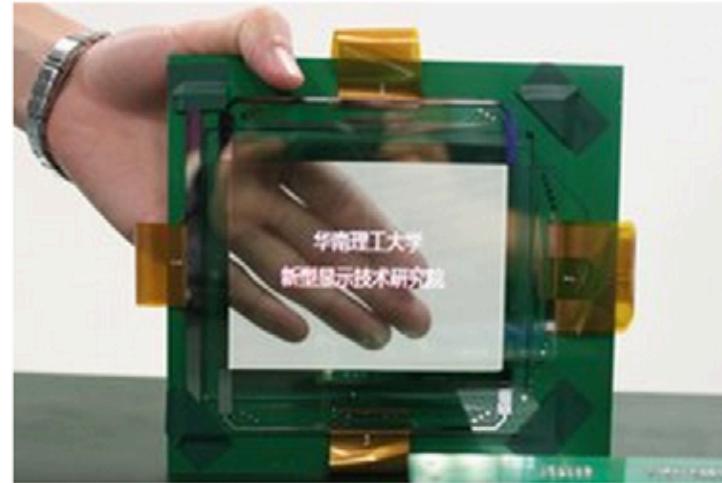
NVO developed their own Ln-IZO (Lithium-Niobate Indium-Zinc-Oxide) technology and they say that it performs better than IGZO as it has higher electron mobility and stability and it is easier to process.

Aug 11, 2013 [read more](#)

SCUT reveals new **Oxide-TFT and transparent** OLED prototypes

Technical / Research [Transparent OLEDs](#) [OLED production](#) [Oxide TFT](#)

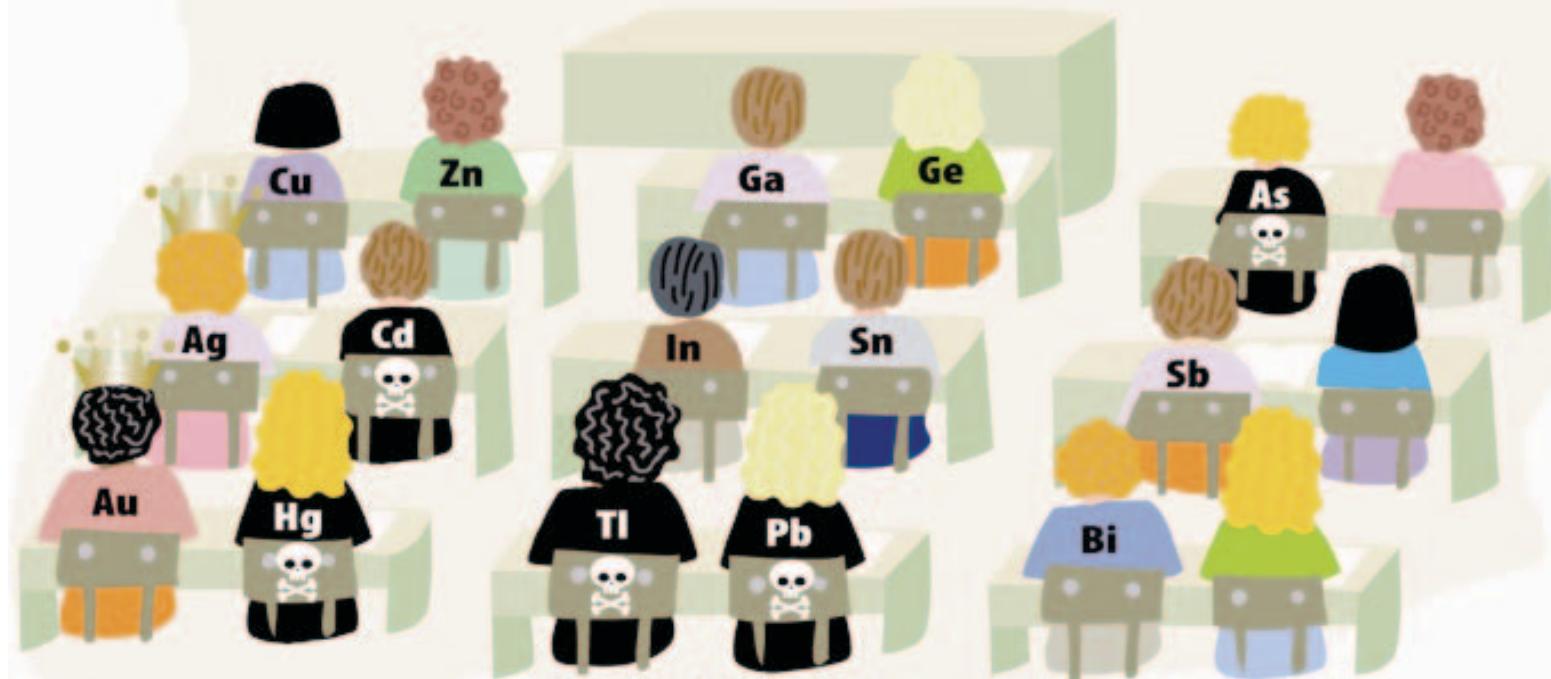
The South China University of Technology (SCUT) unveiled some new AMOLED technologies: a 5" [transparent AMOLED](#) panel, an Oxide-TFT based OLED and an integrated touch AMOLED panel.



Metal oxide semiconductors



A New Class of Electronic Materials

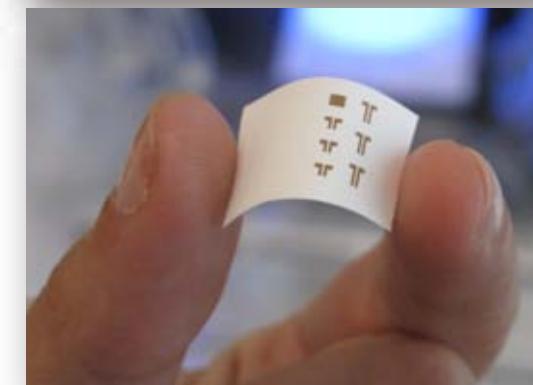
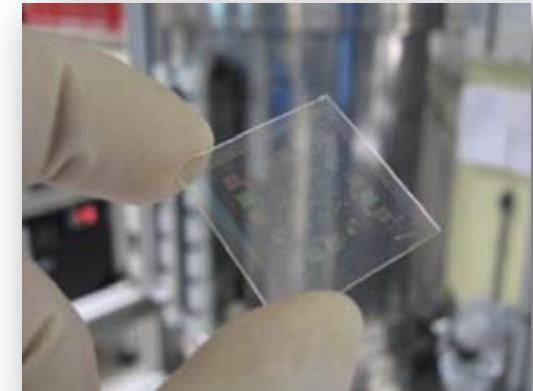


J. Wager, OSU

Why amorphous oxides are so attractive?

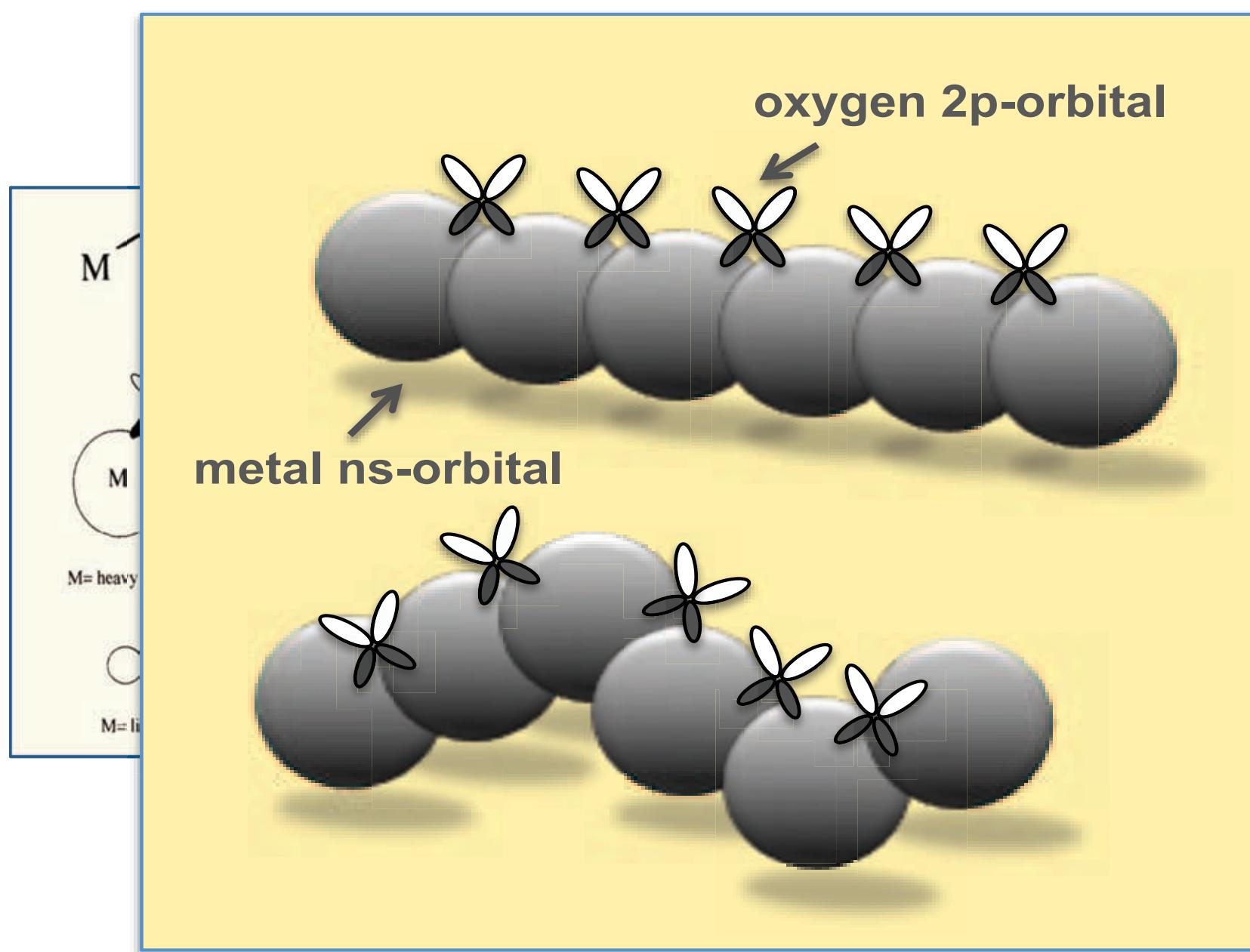
Main advantages

- High electrical performance (μ_{FE} & current: OLEDs)
- Enhanced stability and no visible light-degradation
- Good uniformity in large areas
- Can use the existing processing tools (sputtering)
- AOSs don't need the expensive and demanding Si crystallization processes – they are **AMORPHOUS!!**
- Can be produced at low temperatures, allowing to use low cost flexible substrates (even **PAPER**)
- Transparency.



R. Martins, et al. Complementary Metal Oxide Semiconductor Technology With and On Paper, *Advanced Materials*, 23 (2011) 4491–4496.

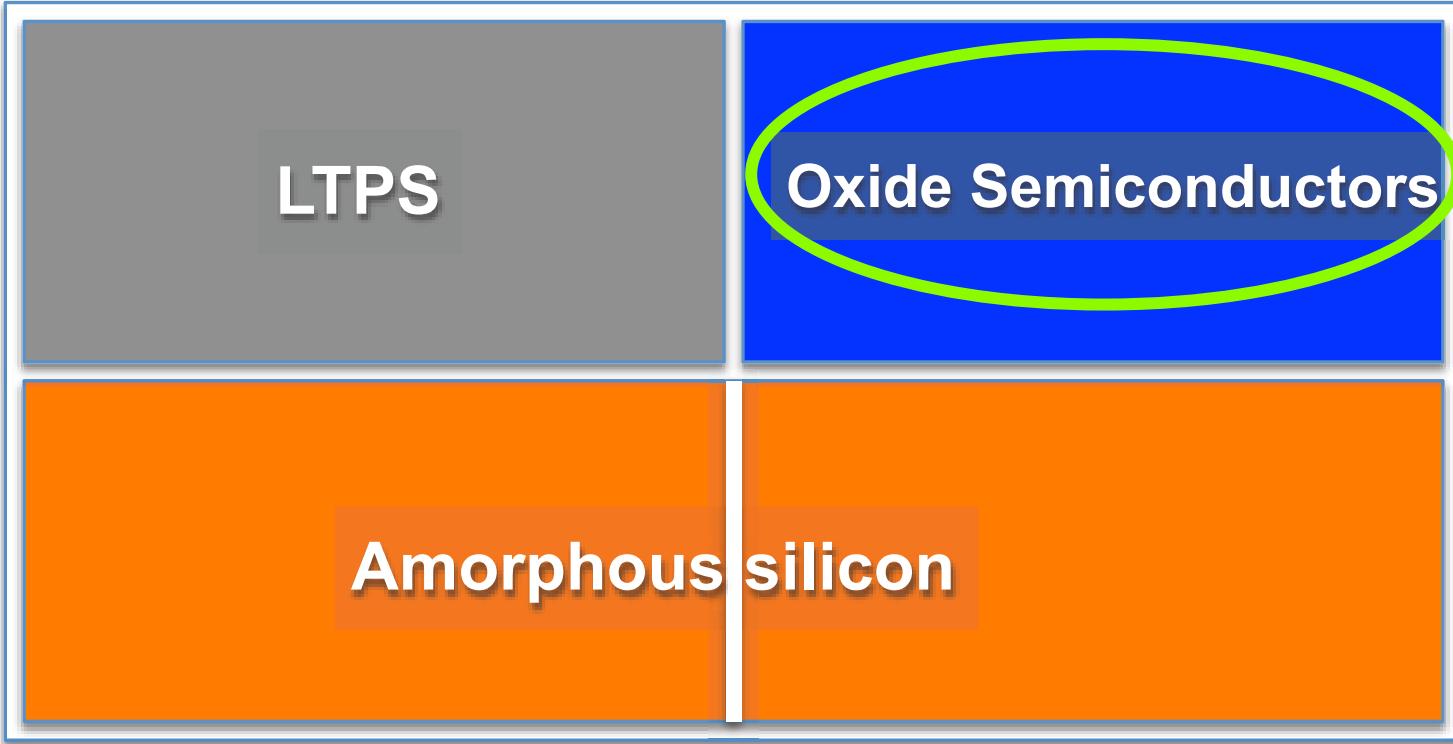
oxygen 2p-orbital



helium	2	He	4.0026
fluorine	9	neon	10
F	Ne	20.180	
18.998		chlorine	17
		argon	18
		Cl	Ar
35.453		39.948	
bromine	35	krypton	36
		Br	Kr
79.904		83.80	
iodine	53	xenon	54
		I	Xe
126.90		131.29	
astatine	85	radon	86
		At	Rn
[21g]		[22g]	

Combine simultaneously, the advantages of amorphous silicon and polycrystalline silicon TFTs

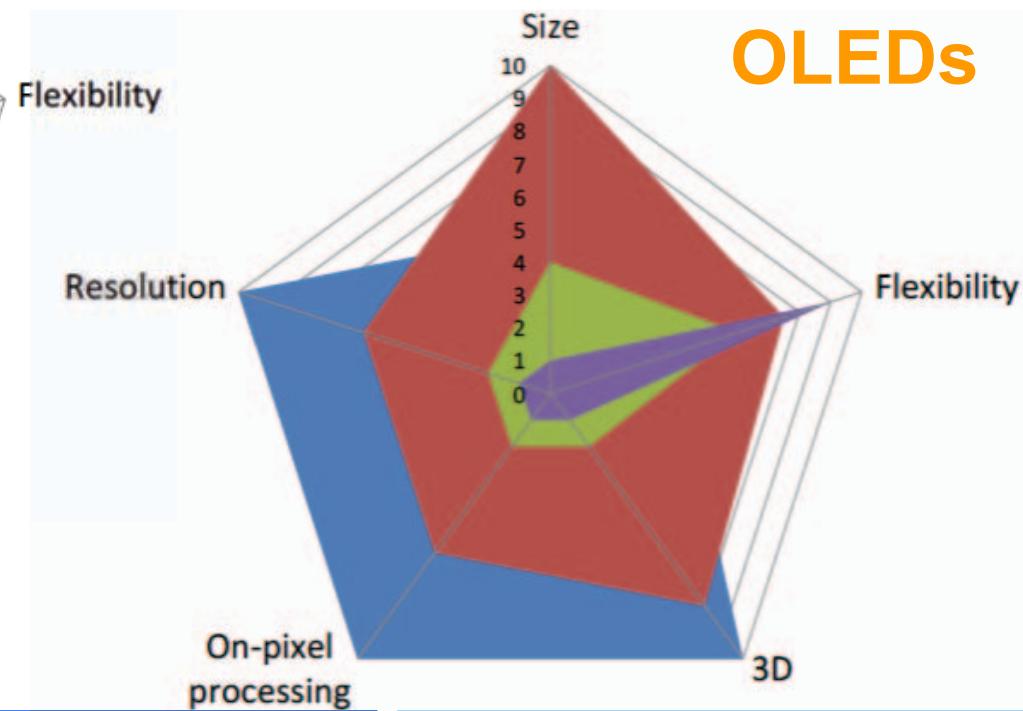
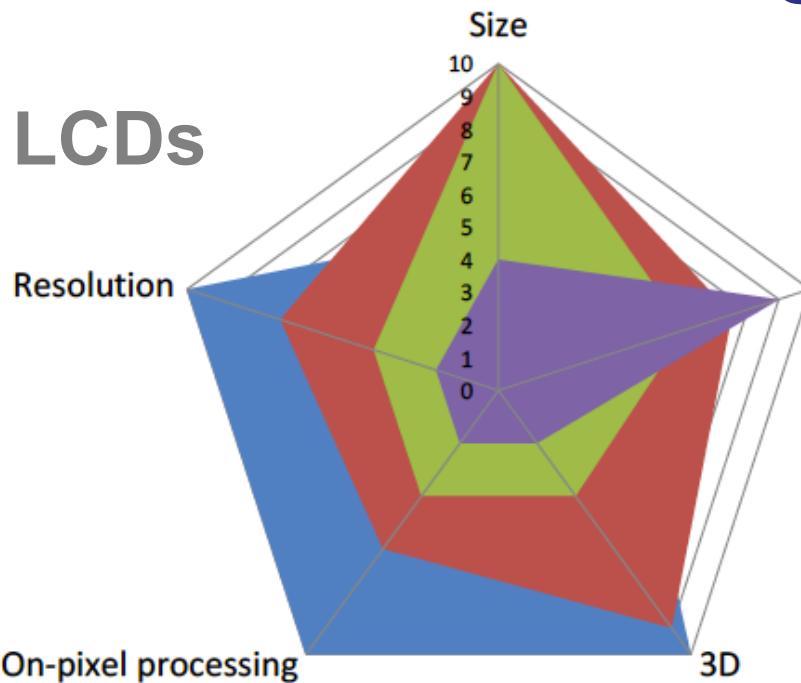
Voltage-Driven Current-Driven



Small-sized

Large-sized

Radar chart assessing the merits of different backplane technologies



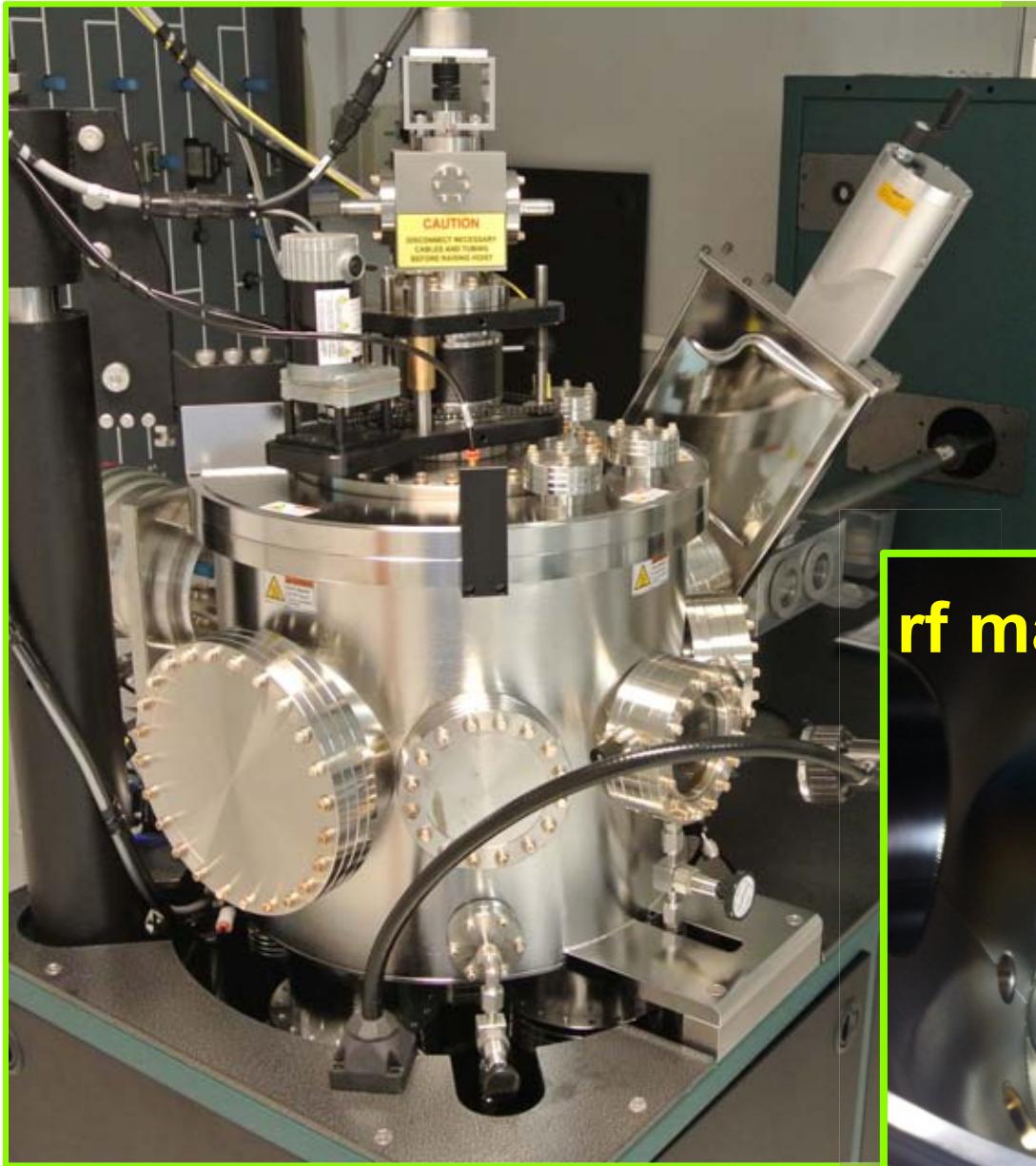
Source: www.IDTechEx.com/

n-type TFTs PVD technique @RT

Main facilities/equipments



Two clean rooms:
classes (1st cycle)
research/contracts

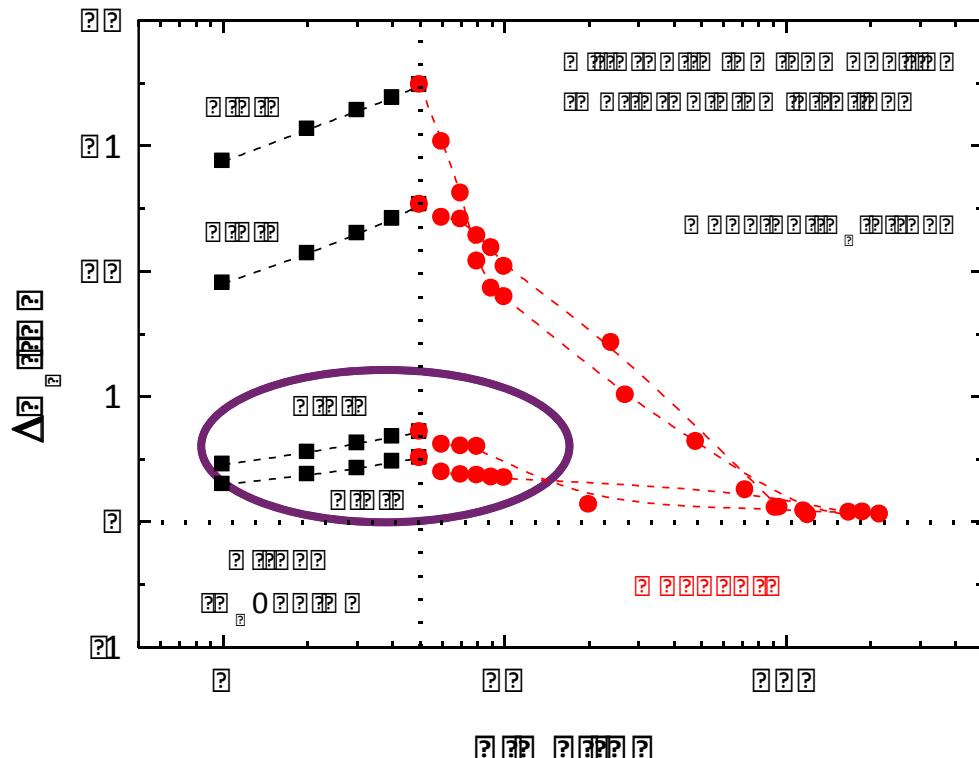
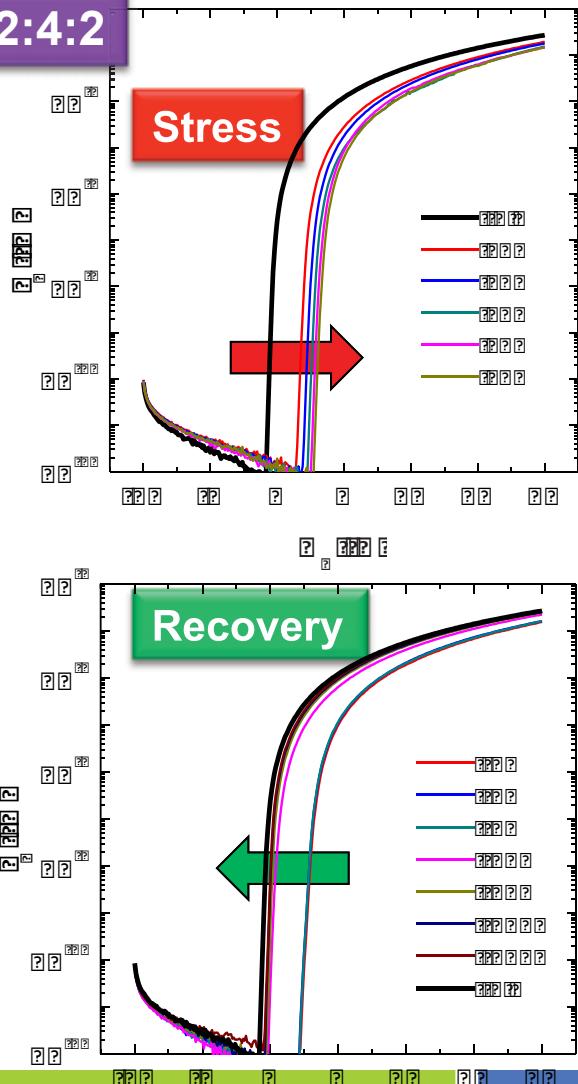


rf magnetron sputtering



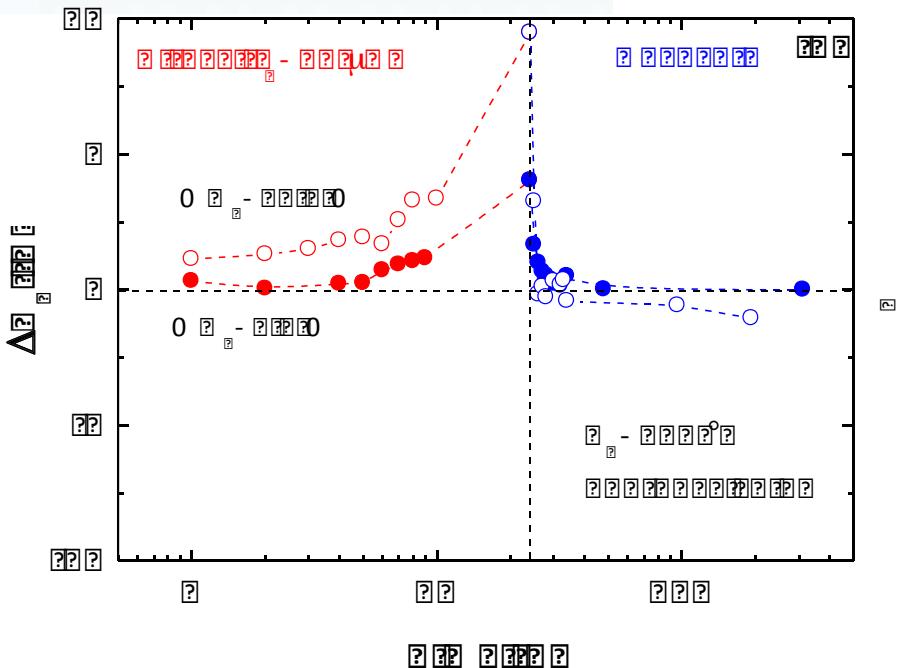
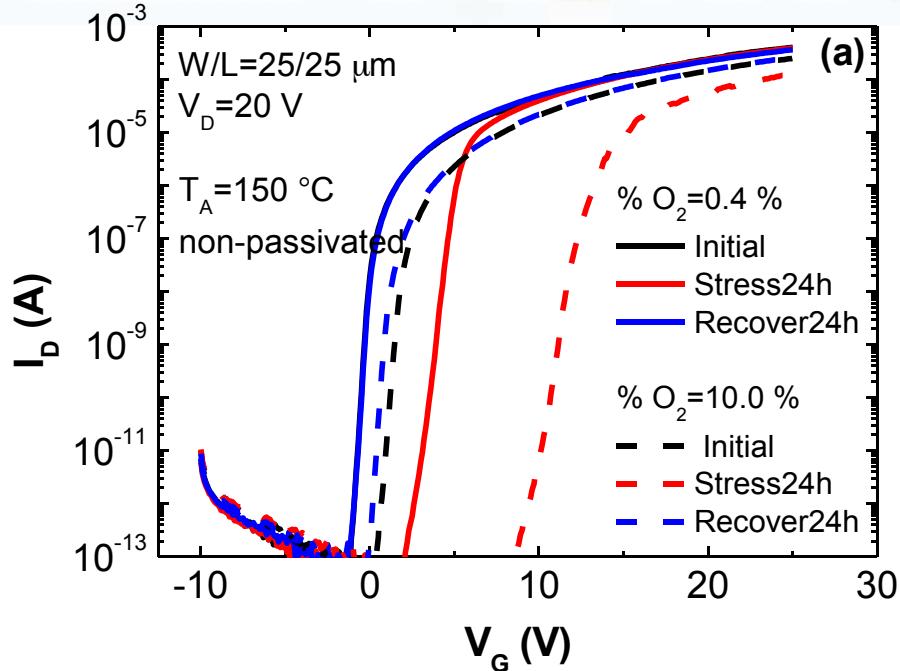
Semiconductor composition

GIZO 2:4:2



- Ga-richer compositions highly unstable under V_G stress (\downarrow carrier concentration, \uparrow structural disorder close to CBM, \uparrow unfilled traps in the unbiased state).
- Similar trends verified with I_D stress.

Effect of O₂ during deposition



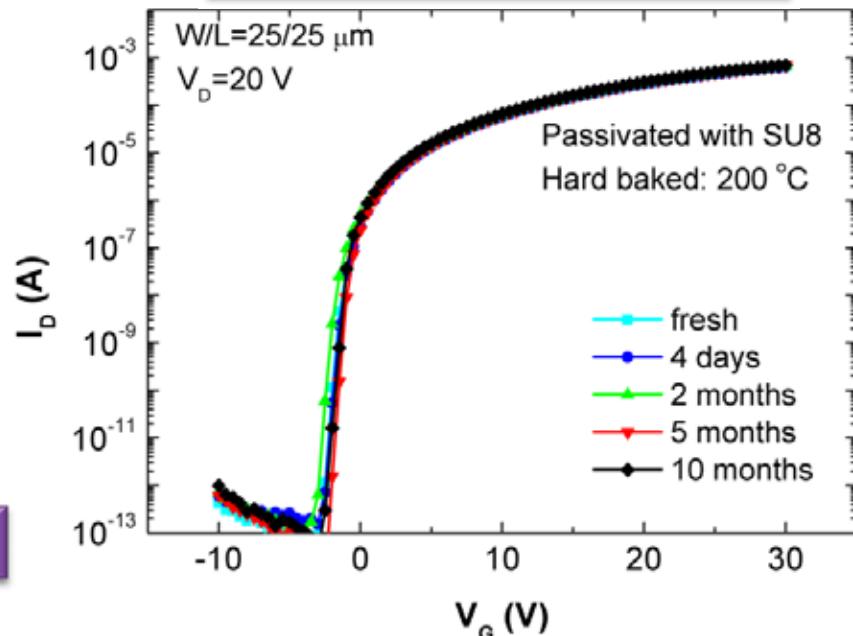
Condition	μ_{FE} (cm ² V ⁻¹ s ⁻¹)	V_{on} (V)	S (V dec ⁻¹)	ΔV_{on} (V)
%O ₂ =0.4 %, $T_A=150 \text{ }^\circ\text{C}$	50.1	-1.0	0.18	≈0
%O ₂ =10.0 %, $T_A=150 \text{ }^\circ\text{C}$	40.8	2.0	0.29	1.5

- ΔV_T and recovery consistent with electron trapping at the semic.and/or dielectric/semic. Interface
- Improved performance and stability for $\downarrow \% \text{O}_2$

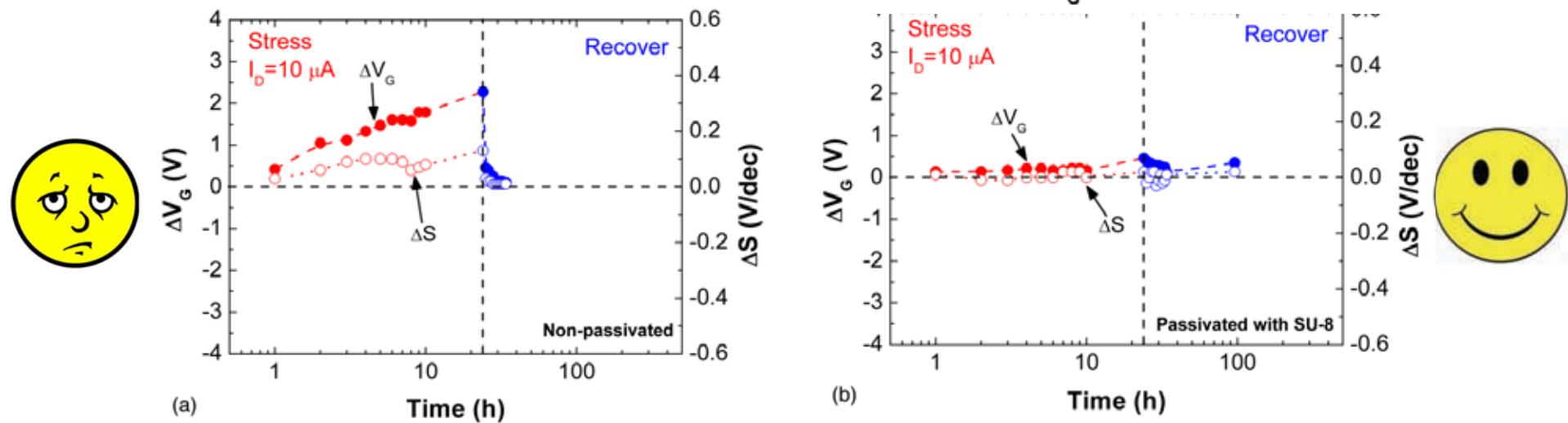
Passivation

Preliminary stability measurements on SU-8 passivated devices

Stability during 10 months



Constant current stress during 24h



Dielectric requirements

All TFT layers

Low T processing



Sputtering



High flexibility

Sputtered dielectrics



Not so good insulating properties

Possible creation of interfacial defects

High k dielectrics

Oxide semiconductor

Dielectric

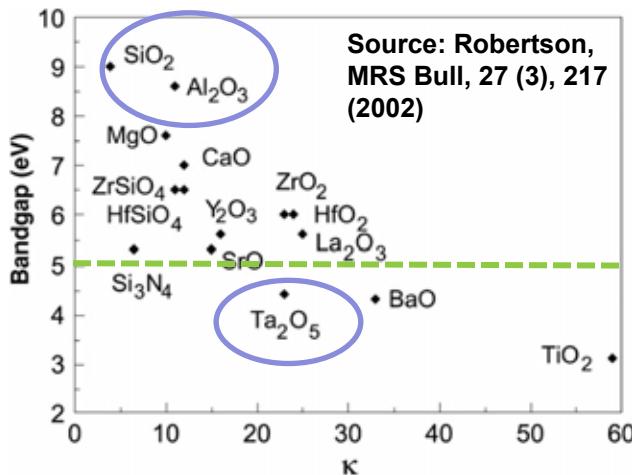
Electrode

Passivation layer

Higher thickness

Reduces interface defects influence

High-k dielectrics



Source: Robertson,
MRS Bull, 27 (3), 217
(2002)

Advantages

High gap (> 5 eV)

High k (20-25)

Disadvantages

Crystallization at low T

Band offset on the limit



Amorphous Multicomponent Dielectrics AMD vs AOS

- Stabilization of an amorphous structure
 - Increase the band gap

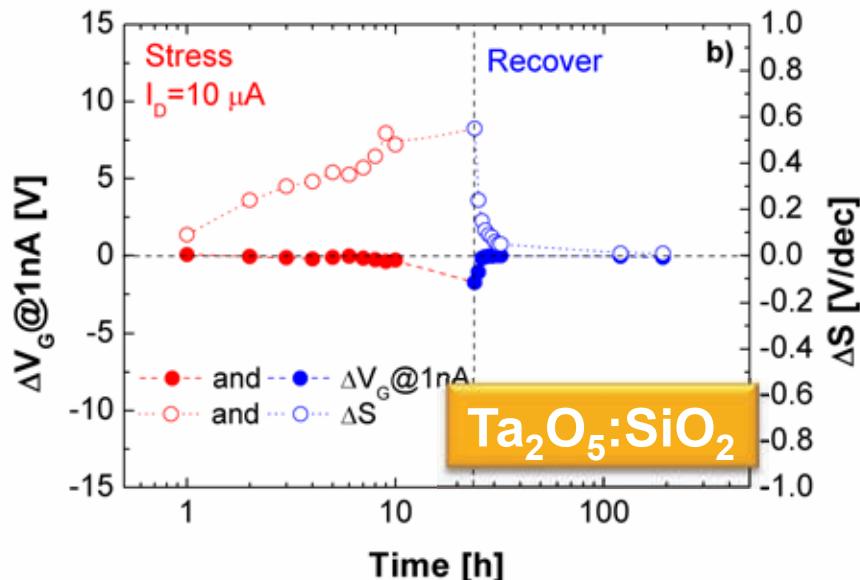
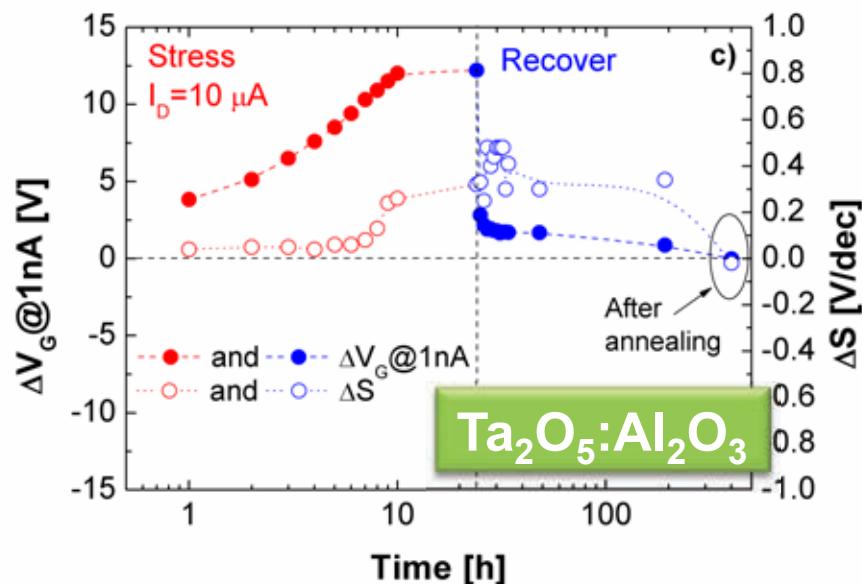
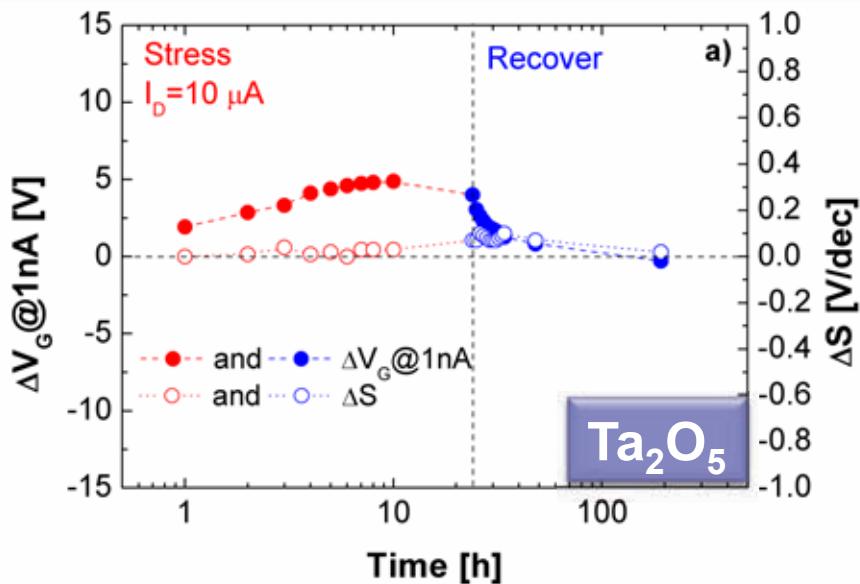
High k T_2O_5



High bandgap

SiO_2
 Al_2O_3

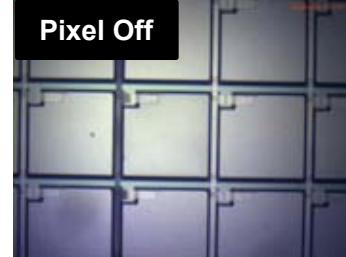
Dielectrics in GIZO TFTs



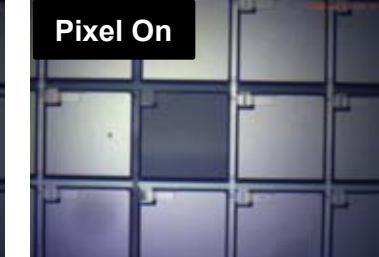
a-GIZO AMLCD



Pixel Off



Pixel On

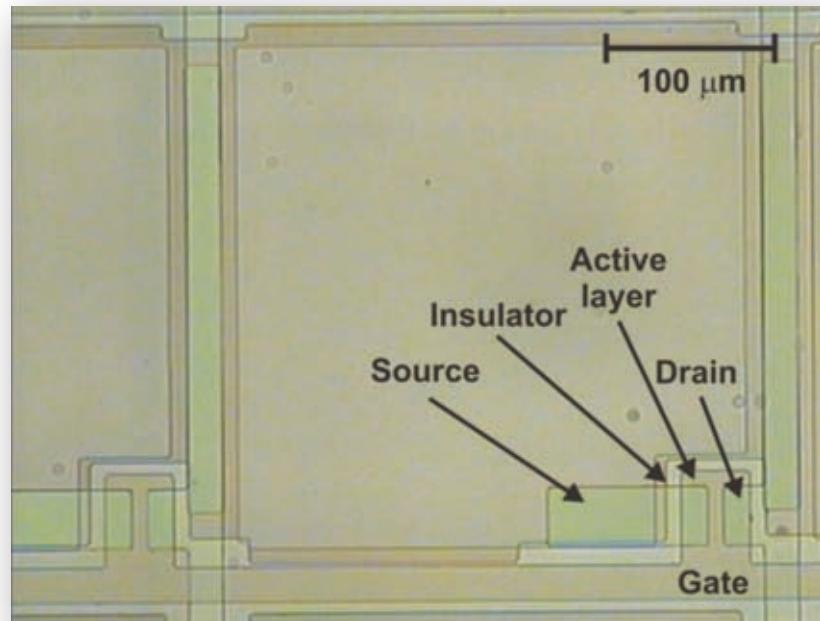


Frontplane:

- Reflective LCD
- White Taylor Guest Host Mode
- Integration by HP @ Bristol/Dublin

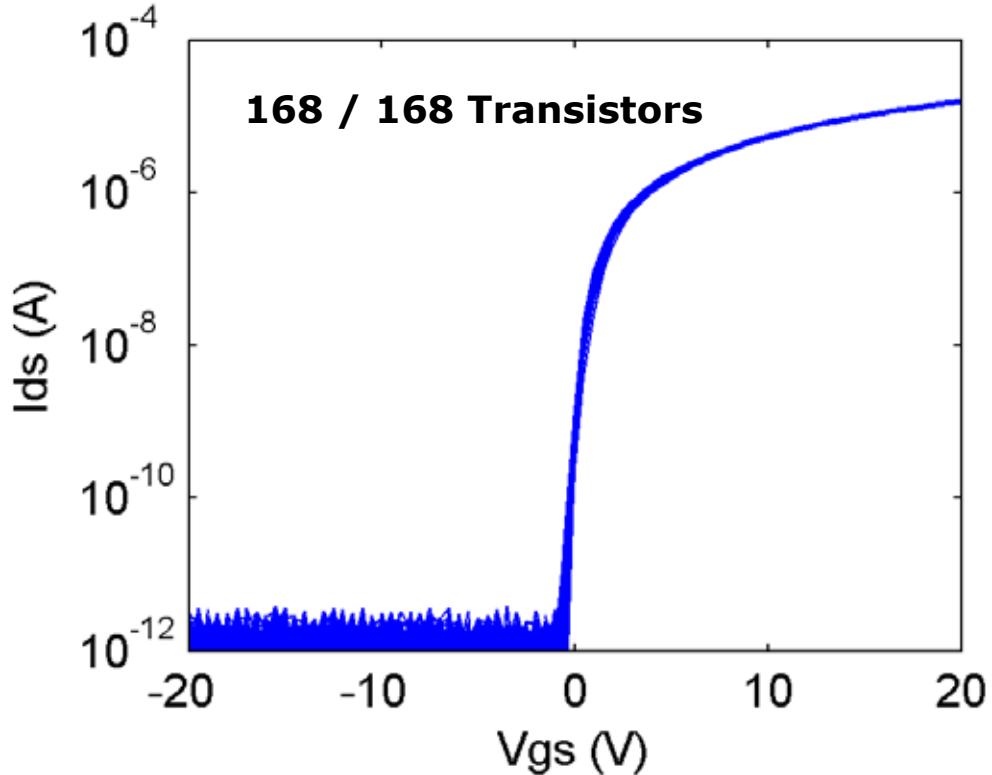
Backplane:

- 5 mask process
- 128x128 pixels, 2.8" diagonal
- Dielectric: co-sputtered $Ta_2O_5-SiO_2$



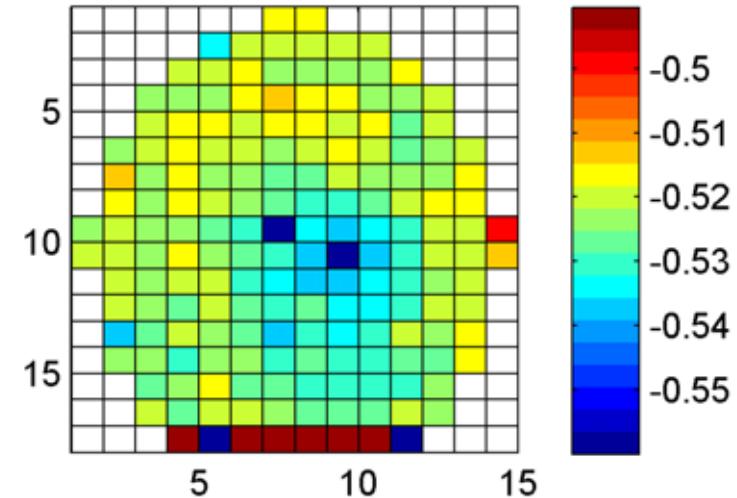
Backplane development: IGZO TFTs on glass

- Mobility $\sim 18 \text{ cm}^2/\text{Vs}$
- Excellent uniformity

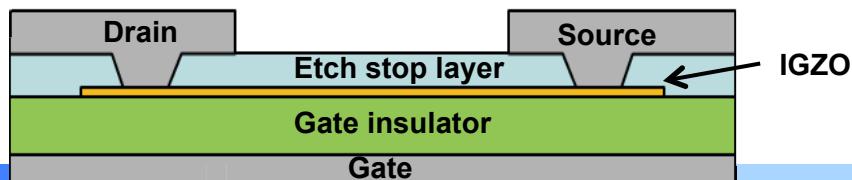


250°C gate insulator
165°C post-fabrication anneal in N₂ oven

Onset Voltage



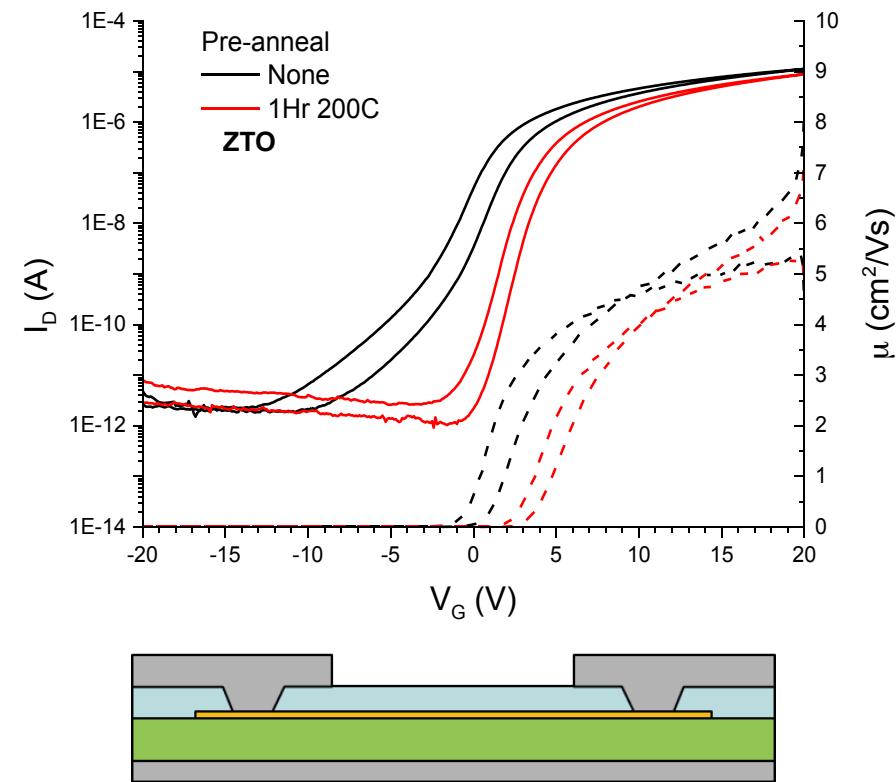
	Mean	Std	
I_{on}	14.22	0.22	uA
V_{on}	-0.53	0.02	V
mob	18.28	0.42	cm ² /Vs



ZTO in PEN-compatible process

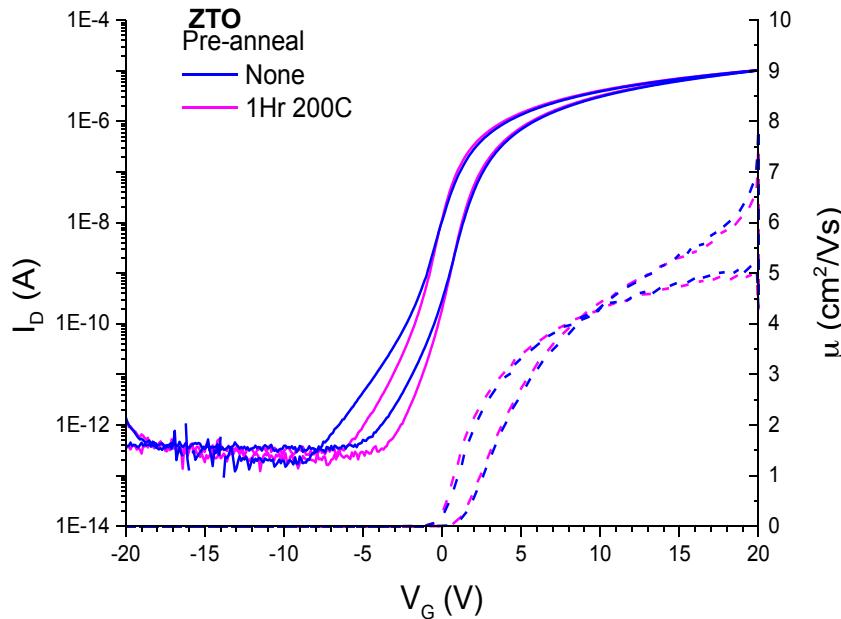


1 hr post-fabrication anneal



180°C gate insulator
165°C Post-fabrication anneal in N₂ oven

4 hr post-fabrication anneal



Mobilities as expected for <200°C process

Display Demo using PVD on Flexible Substrates



IGZO Displays

QQVGA displays

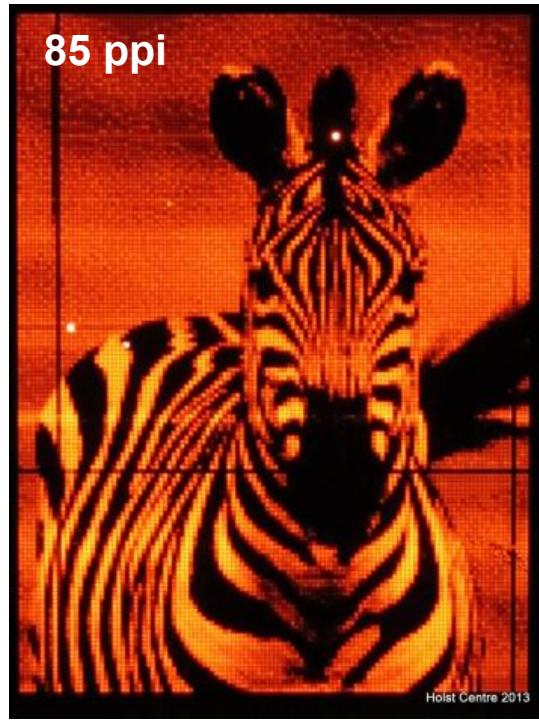


Gray level control possible



Debonded flexible display
IGZO backplane on PEN

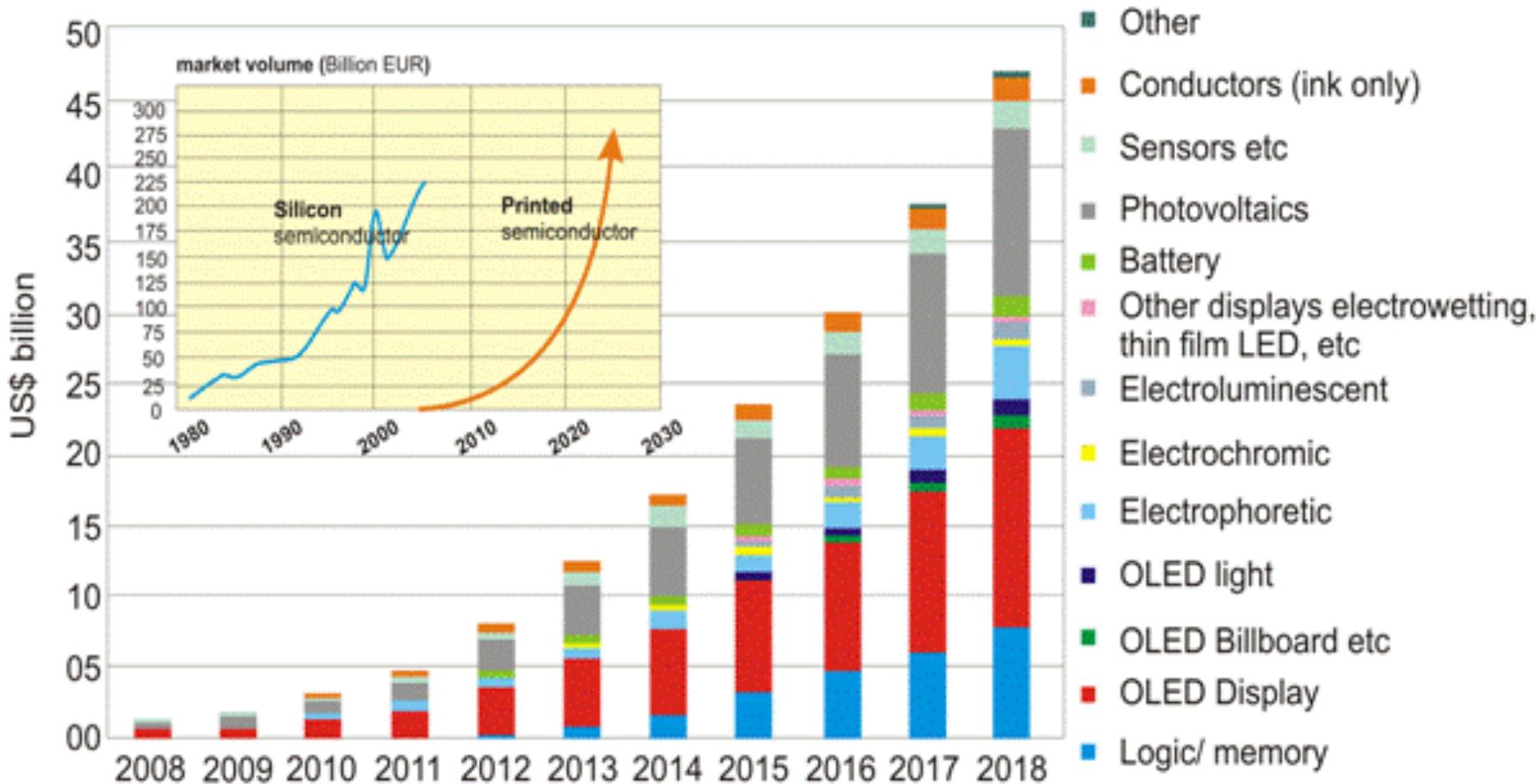
Display Demo Status Overview



Diagonal	4.0 inch	1.0 inch	0.5 inch
Rows x Columns	120x160	120x160	64x160
Pixel Size	300 µm x 300 µm	127 µm x 127 µm	80 µm x 80 µm
Resolution	85 ppi	200 ppi	320 ppi
Pixel Circuit	2T + 1C	2T + 1C	2T+1C, integrated row driver
OLED Structure	Top-Emission	Top-Emission	Top-Emission
Substrate	PEN	PEN	PEN

n-type TFTs Solution-based

Printed electronics

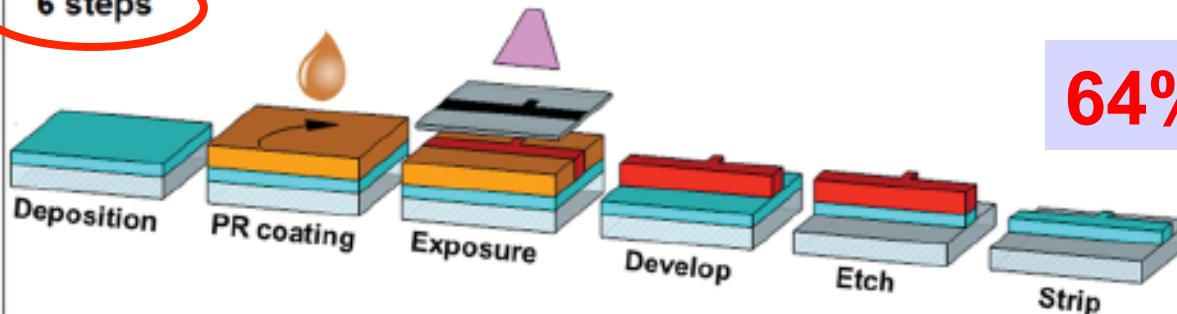


Source: *IdTechEx*

Needs for cost reduction

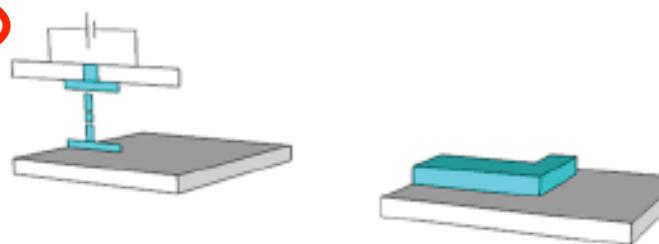
Vacuum and Photolithography Process

6 steps

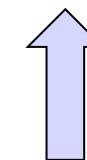


Printing Process

1 step



64% cost reduction!!!



Vacuum systems

42%

Photolithography

22%

Etching

14%

Back-end

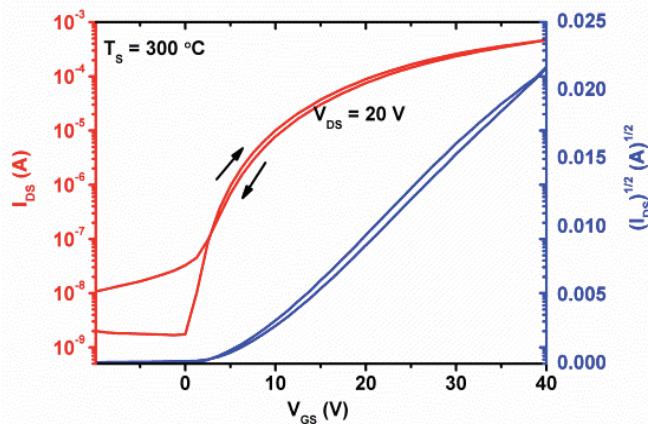
14%

Facilities

8%

Solution processed n-type oxide TFTs – on ITO/ATO

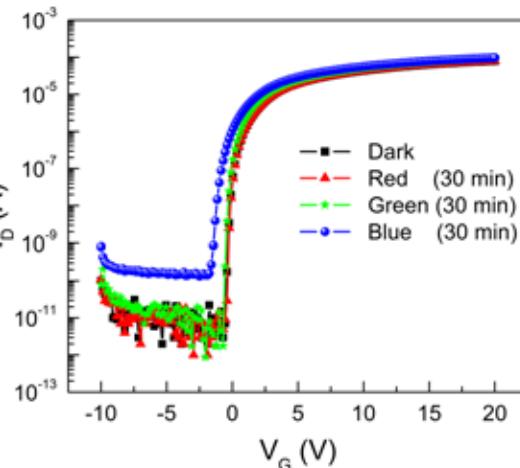
ZTO by spray-pyrolysis, $T_{dep}=300\text{ }^{\circ}\text{C}$



$\mu_{FE} \approx 1 \text{ cm}^2/\text{Vs}$
On/Off $\approx 10^5$
 $V_{on} \approx 0 \text{ V}$
 $S \approx 0.6 \text{ V/dec}$

Shanmugan et al. JDT (2013)

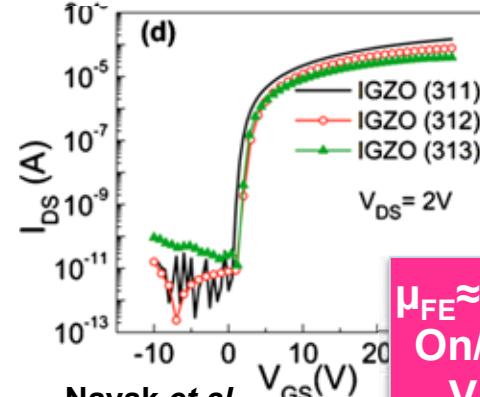
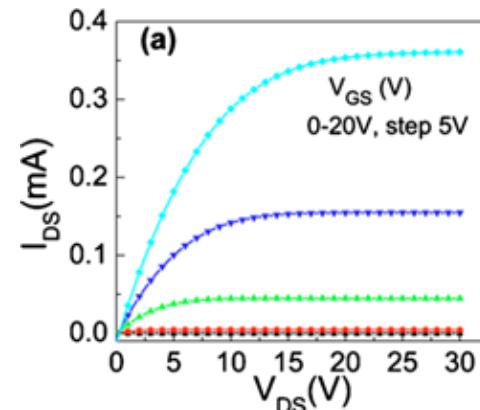
ZTO by spin-coating,
 $T_A=500\text{ }^{\circ}\text{C}$



$\mu_{FE} \approx 5 \text{ cm}^2/\text{Vs}$
On/Off $\approx 10^8$
 $V_{on} = -0.9 \text{ V}$
 $S \approx 0.2 \text{ V/dec}$

Nayak et al., JDT 7, 640
(2011)

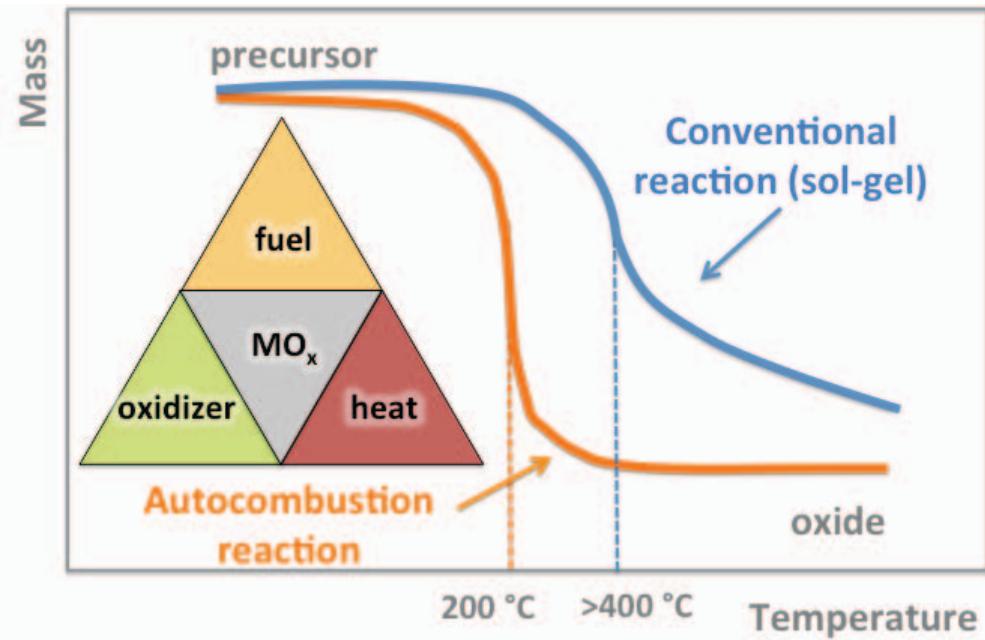
GIZO by spin-coating,
 $T_A=400\text{ }^{\circ}\text{C}$



Nayak et al.,
APL 97 183504
(2010)

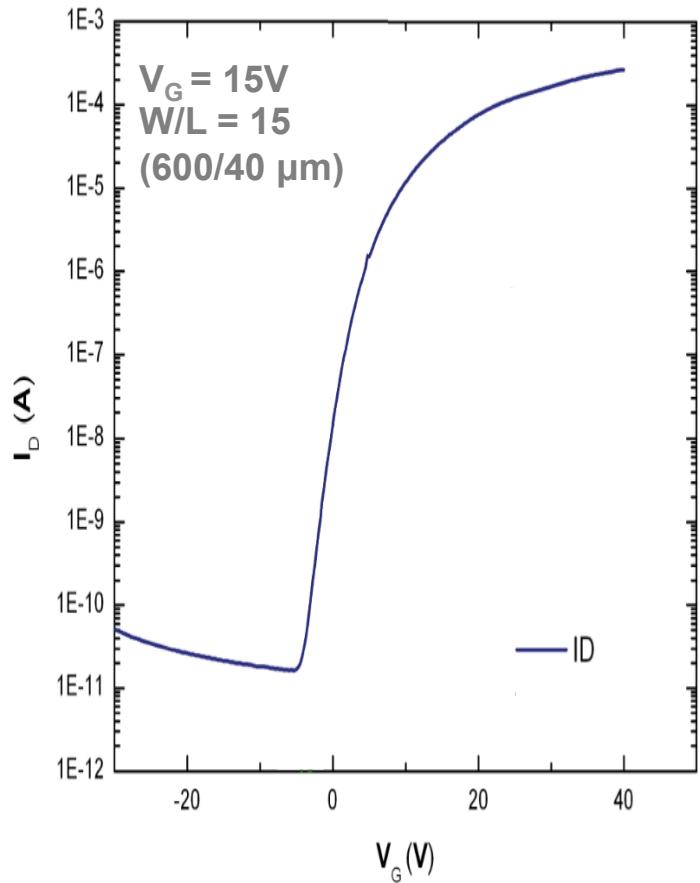
$\mu_{FE} \approx 5 \text{ cm}^2/\text{Vs}$
On/Off $\approx 10^7$
 $V_{on} \approx 0 \text{ V}$
 $S = 0.28 \text{ V/dec}$

GZTO TFTs (combustion) on ITO/ATO



**Ga:Zn:Sn = 2:1:0.1 in
Methoxyethanol @ 250 °C**

$$I_{on}/I_{off} = 10^7$$
$$\mu = 6 \text{ cm}^2/\text{Vs}$$



n-type TFTs MO nanoparticles (electrolyte-gated)

Electrolyte gated NPs TFTs

ZnO NPs

Dielectric interface

Conventional dielectric



Metal oxide
nanoparticles

Dielectric
thin film

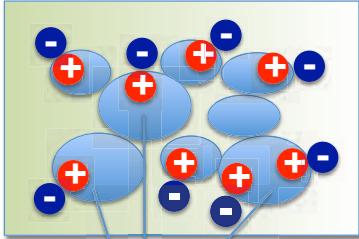
Gate electrolyte



Liquid electrolyte
(after drying becomes solid)

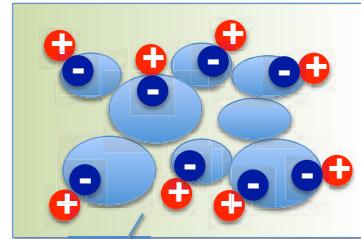
Device working principle (interface electrolyte-channel layer)

OFF-state ($V_G < 0$ V)

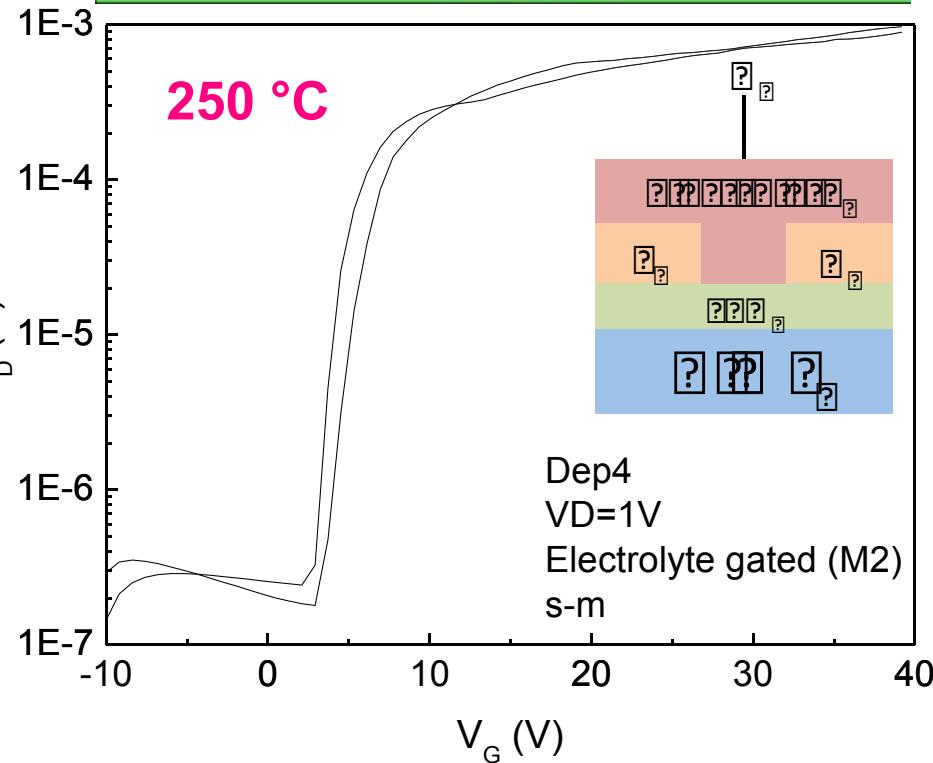
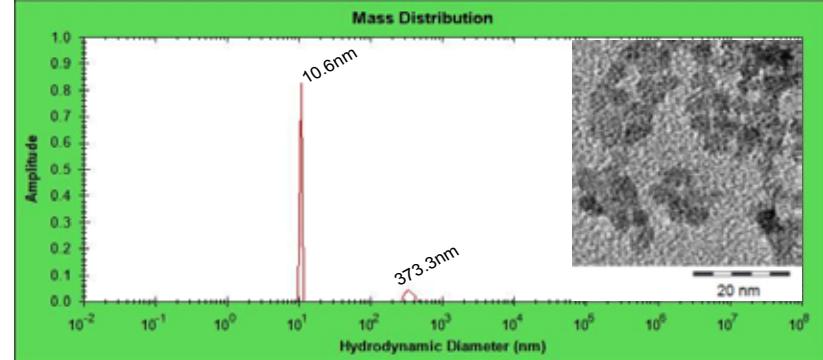


Channel n-type nanoparticles

ON-state ($V_G > 0$ V)



Electrolyte

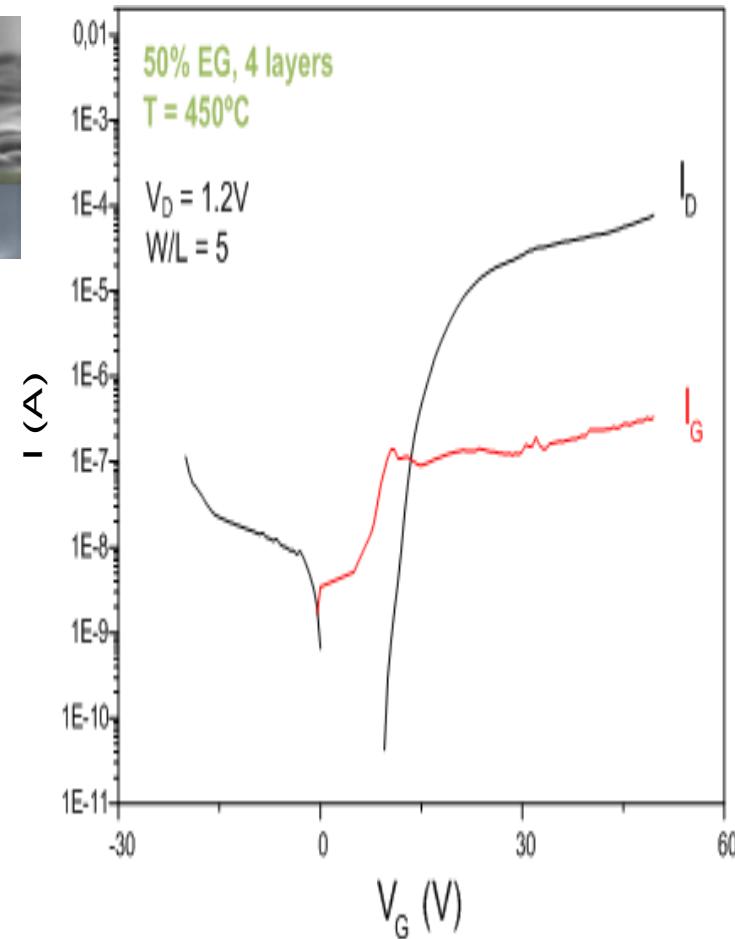
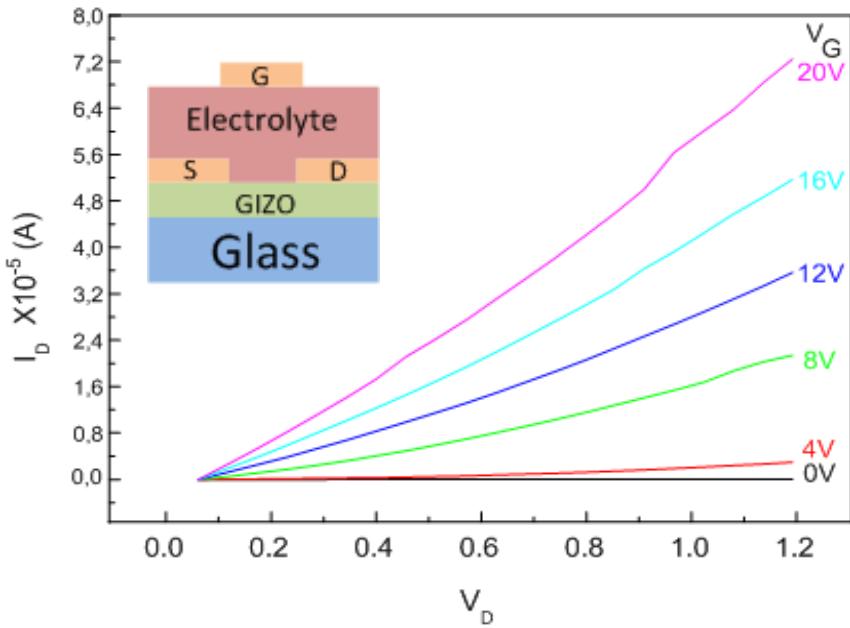
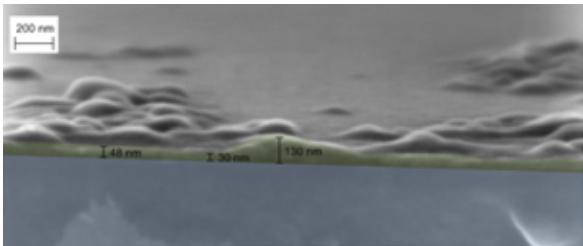


Electrolyte gated NPs GIZO TFTs

$I_{ON}/I_{OFF} = 4 \times 10^6$

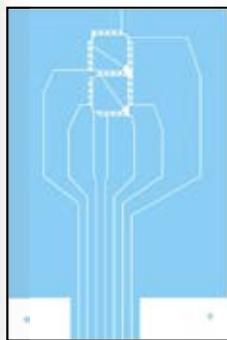
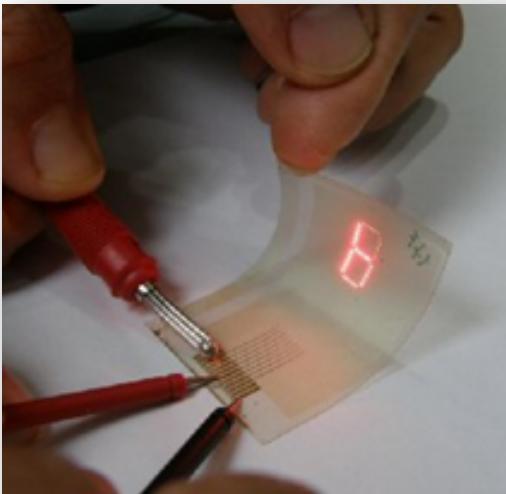
$V_T = 13 \text{ V}$

$\mu_{SAT} \approx 0.1 \text{ cm}^2/\text{Vs}$



Passive and active matrix backplanes

IZO electrodes as a passive matrix for chipLED



- Alphanumeric, 7 segments
- For HUD application in automotive industry

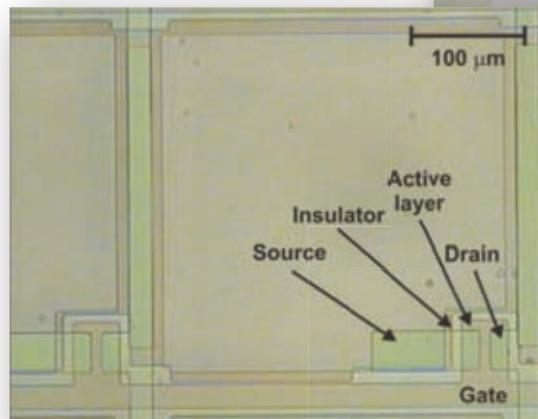
Collaboration with
Centro Ricerche
Fiat (CRF)

In the framework of Multiflexioxides FP6 project

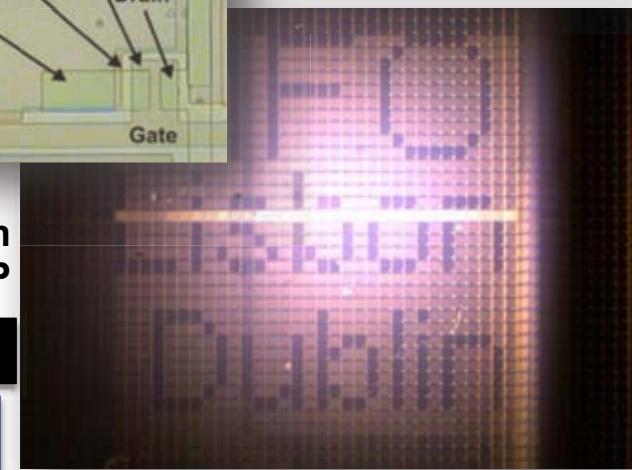
Material/devices properties significantly enhanced from then...

GIZO TFTs for active matrix of LCD display

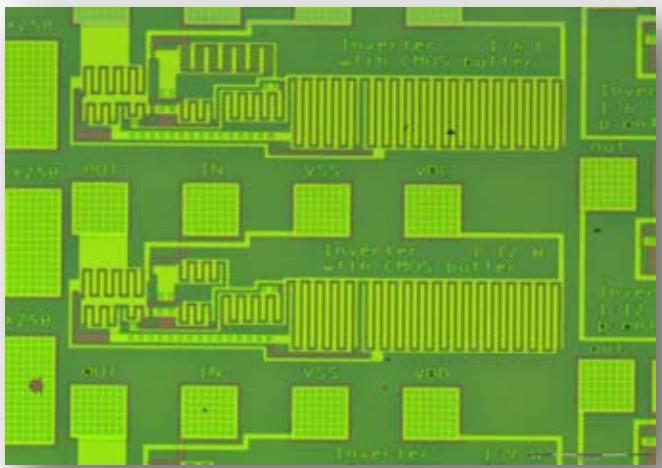
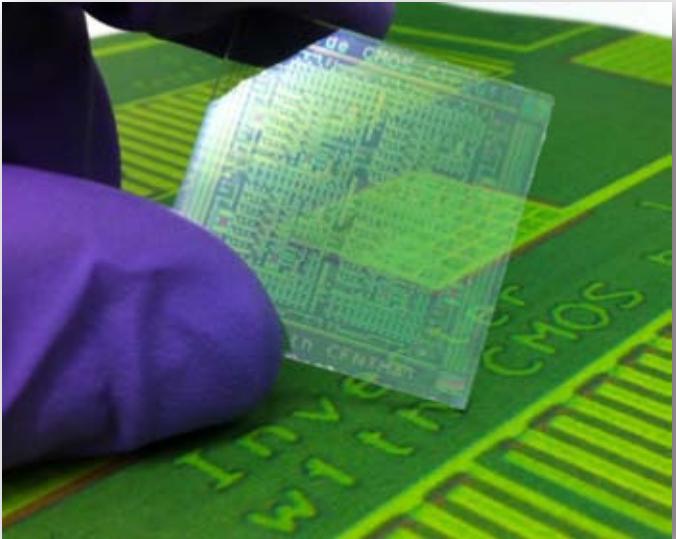
- Resolution: 128x128
- Pixel area: $350\mu\text{m} \times 350\mu\text{m}$
- 5 mask process



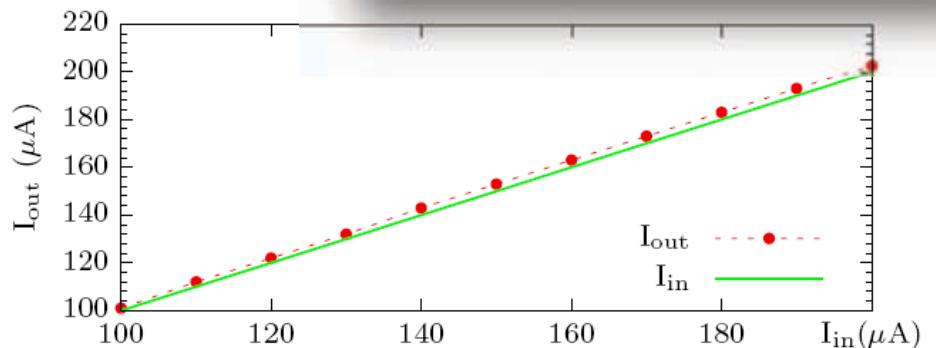
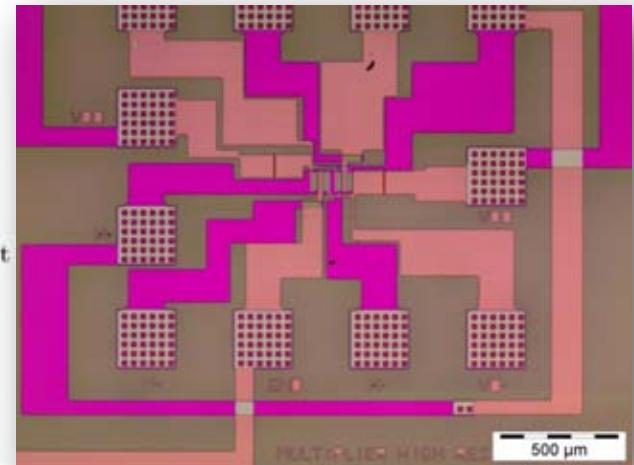
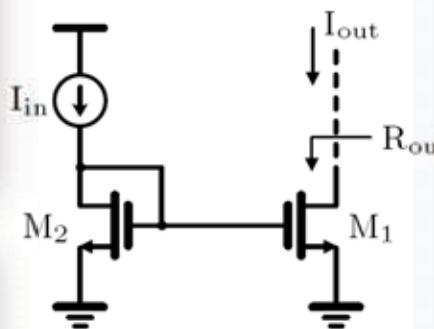
Collaboration
with HP



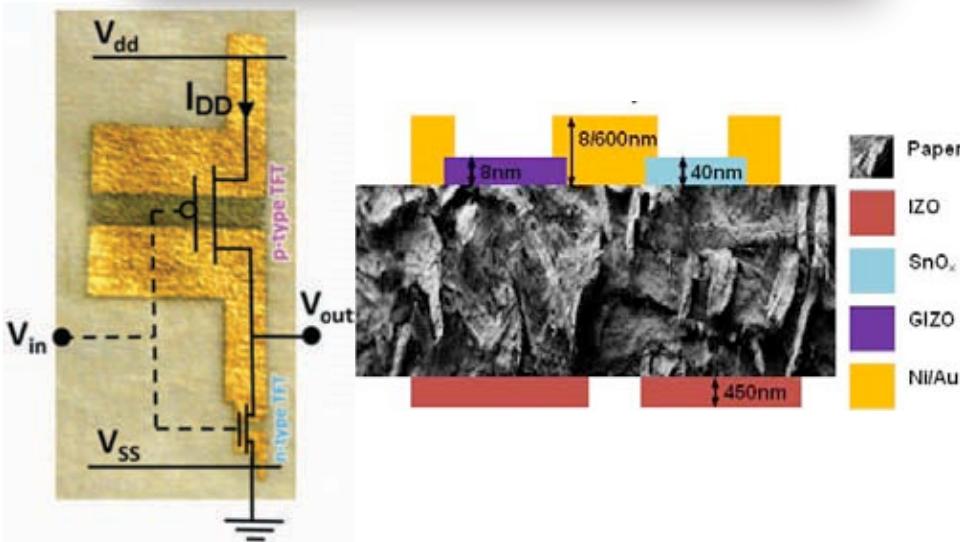
Transparent circuits



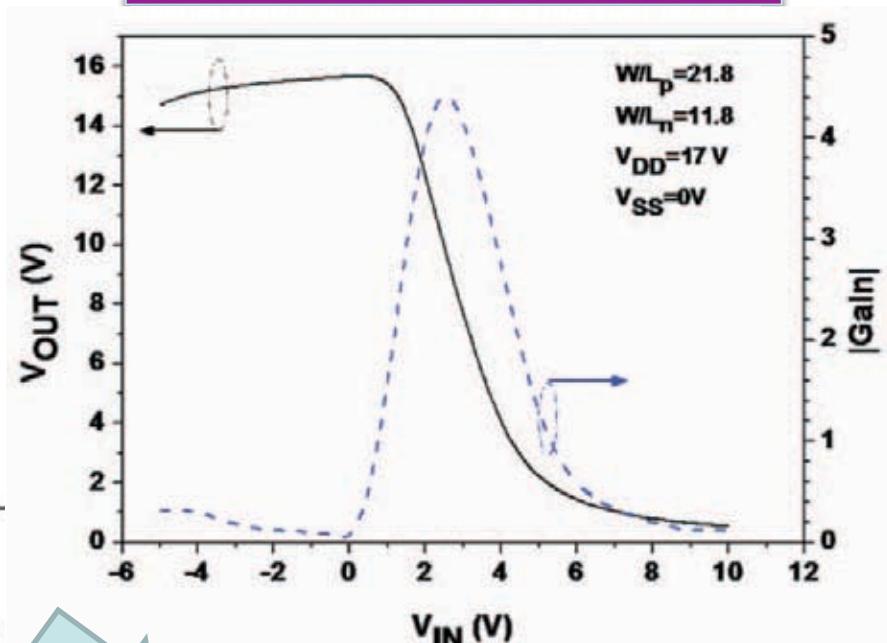
- Using n-MOS technology (GIZO for now) and multilayer/multicomponent dielectrics
- Simple transparent circuits such as inverters, current mirrors, multipliers, with $T_{MAX}=150\text{ }^{\circ}\text{C}$
- Complete characterization underway...



Paper electronics (Paper-e®)



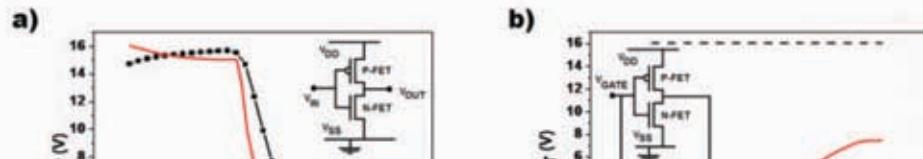
- Even CMOS with GIZO and SnO already possible...
- ...even with paper.



Towards low-cost, recyclable
electronics



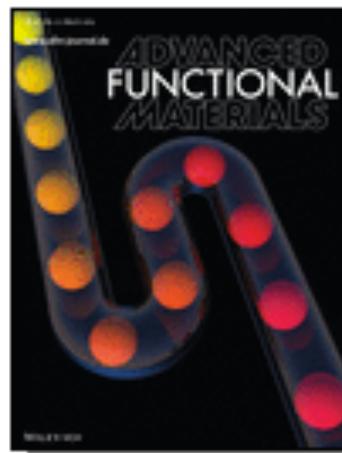
Logic circuits on/with paper



Recyclable, Flexible, Low-Power Oxide Electronics

Rodrigo F. P. Martins^{1,*}, Arman Ahnood²,
Nuno Correia¹, Luís M. N. P. Pereira¹,
Raquel Barros¹, Pedro M. C. B. Barquinha¹,
, Ricardo Costa¹, Isabel M. M. Ferreira¹,
Arokia Nathan^{2,*}, Elvira E. M. C. Fortunato
1,*

Issue



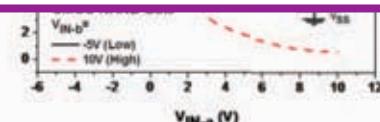
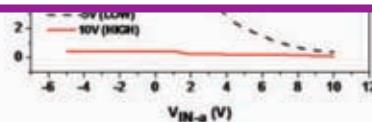
Advanced Functional Materials

Volume 23, Issue 17, pages 2153–2161, May 6, 2013

Article first published online: 29 NOV 2012

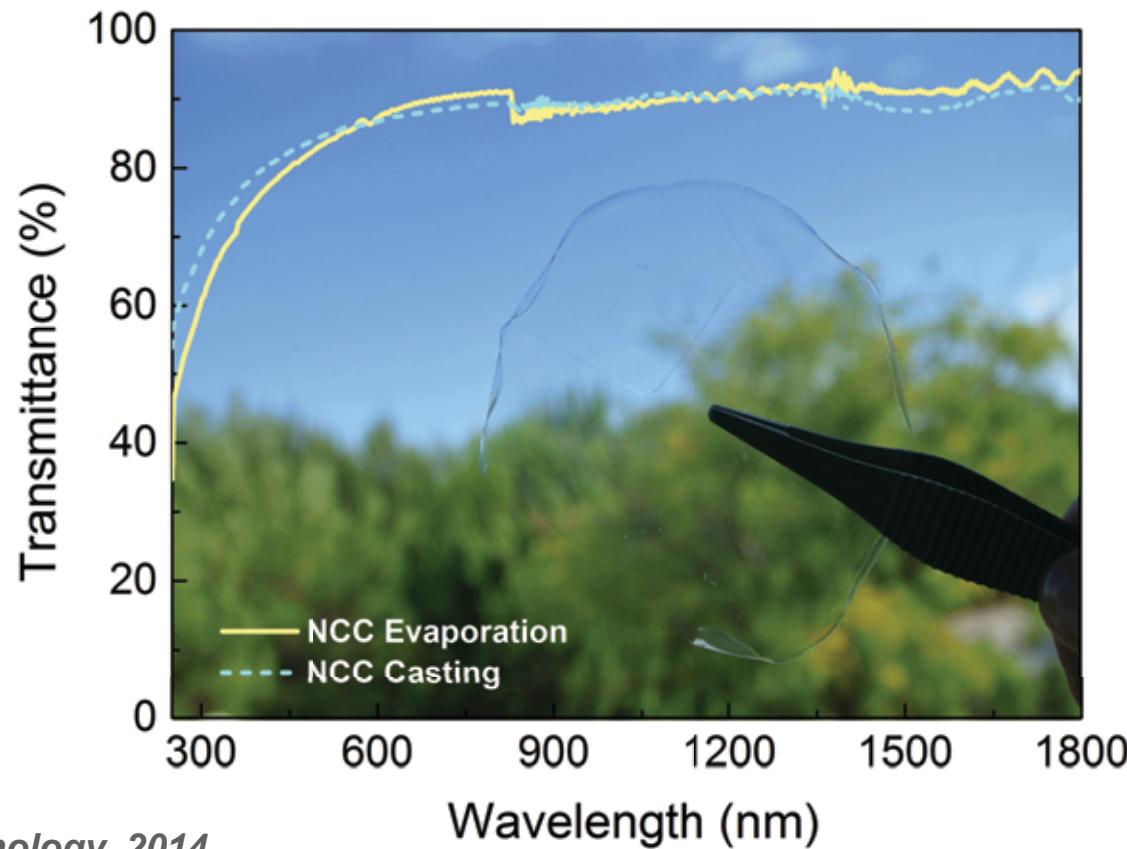
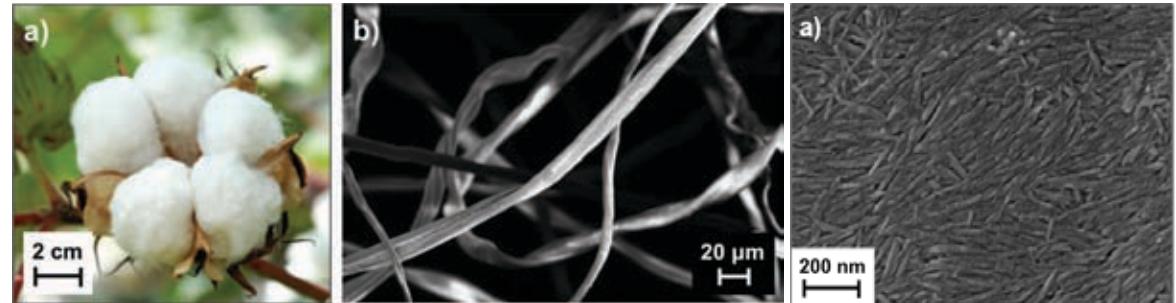
DOI: 10.1002/adfm.201202907

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Co. KGaA, Weinheim



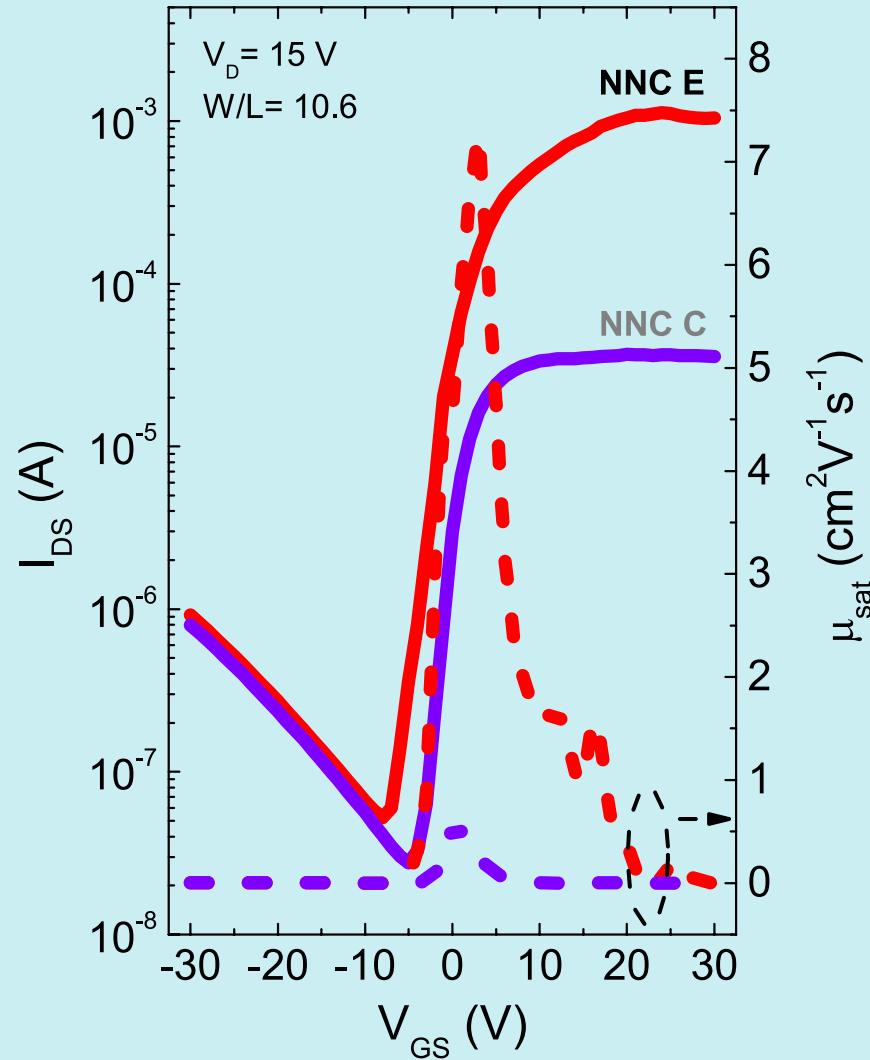
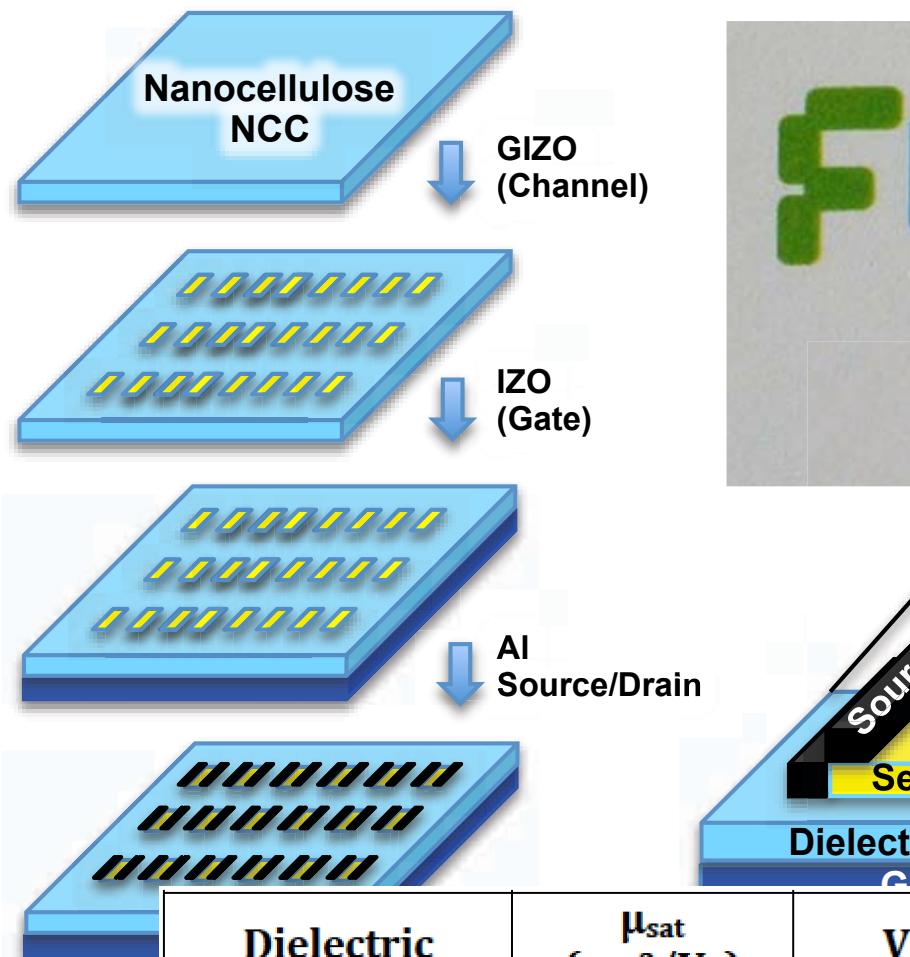
R. Martins et al., *Adv. Func. Mat.* 201202907, 2012

Nanopaper (cotton fibers)



Accepted Nanotechnology, 2014

Nanopaper transistor



Dielectric	μ_{sat} (cm^2/Vs)	V_{ON} (V)	I_{ON}/I_{OFF}	S (V/dec)
NCC evaporation	7.27	-8	2×10^5	2.11
NCC casting	0.54	-5	1×10^4	1.79

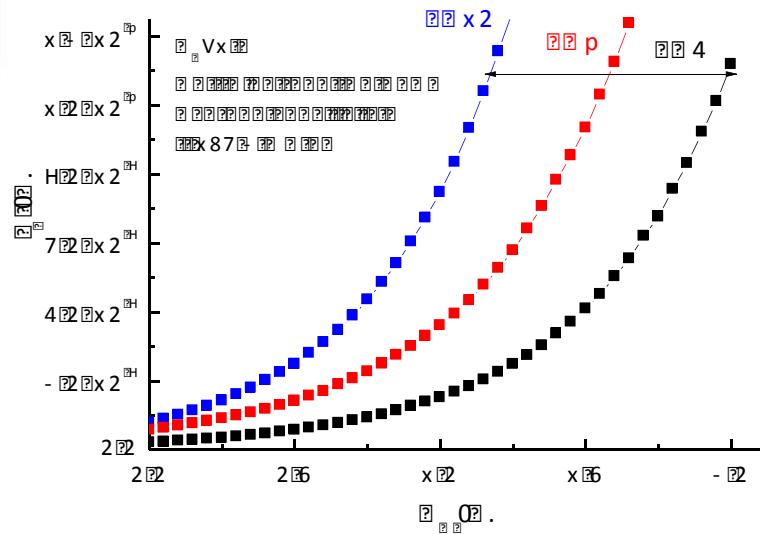
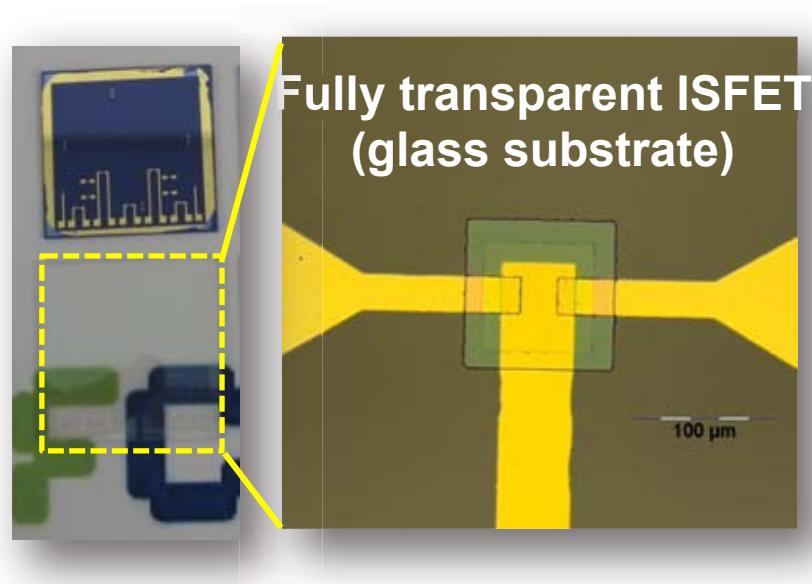
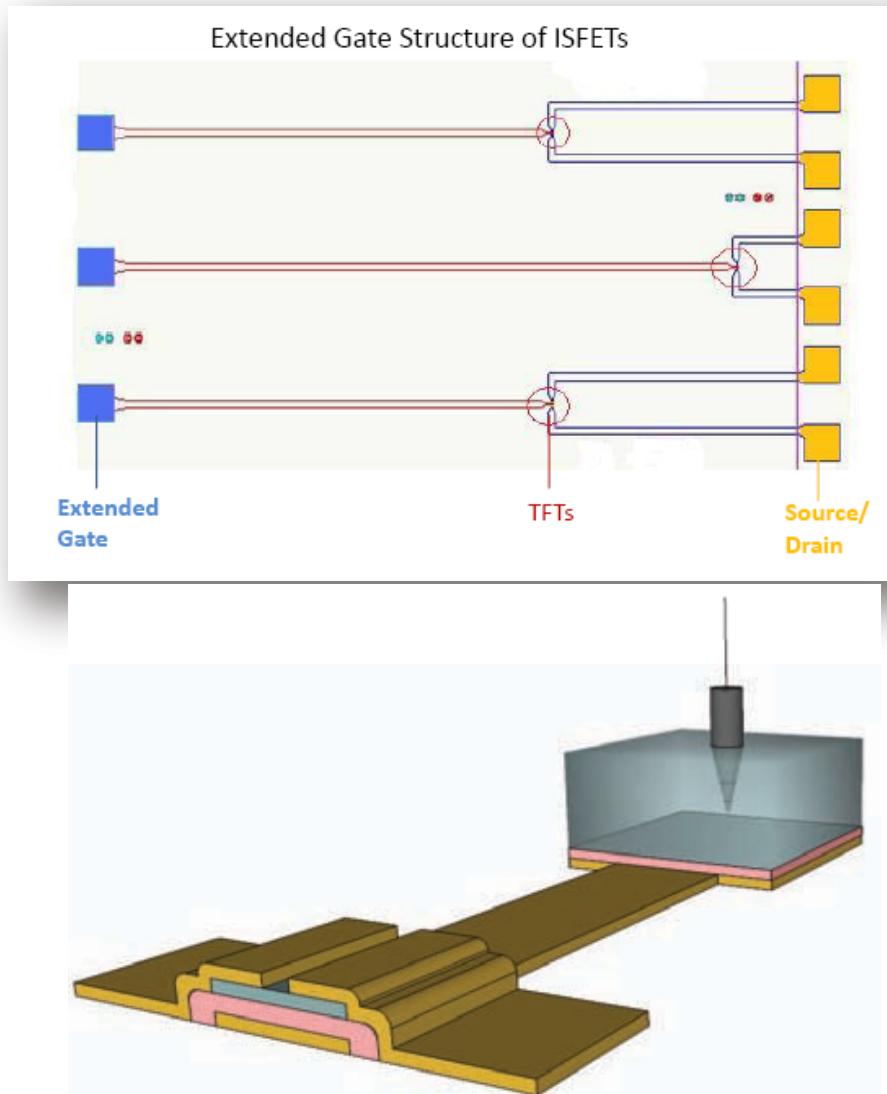
General conclusions

- | | | |
|------------------------------|---|---|
| Amorphous structure |  | Large area uniformity |
| Superior performances |  | High mobility |
| Transparency |  | Specific applications |
| Stability |  | Aging effects not existing |
| Electrical stability |  | No current bias stress |
| Passivation |  | Already achieved |
| Simple structure |  | Reduced process steps,
no need of n⁺ contacts |

Ideal oxide material for TFT application:

- **high carrier mobility**
- **low carrier concentration**
- **non-vacuum deposition**
- **low temperature deposition**

Biosensors / ISFETs





All Oxide Solar Cells

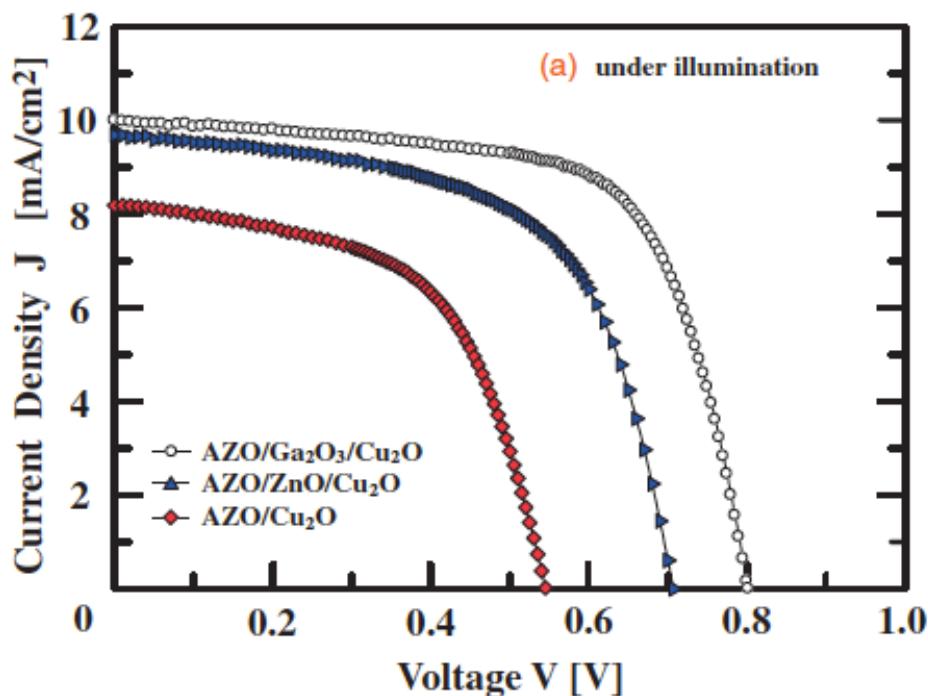
<http://alloxidepv.eu/>

High-Efficiency Cu₂O-Based Heterojunction Solar Cells Fabricated Using a Ga₂O₃ Thin Film as N-Type Layer

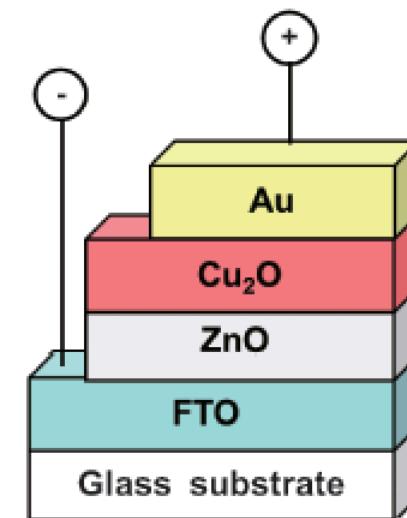
Tadatsugu Minami, Yuki Nishi, and Toshihiro Miyata

Optoelectronic Device System R&D Center, Kanazawa Institute of Technology, Nonoichi, Ishikawa 921-8501, Japan

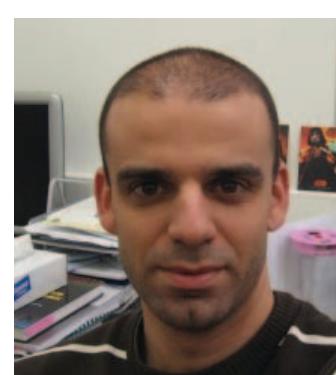
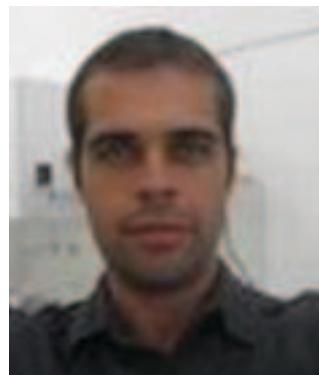
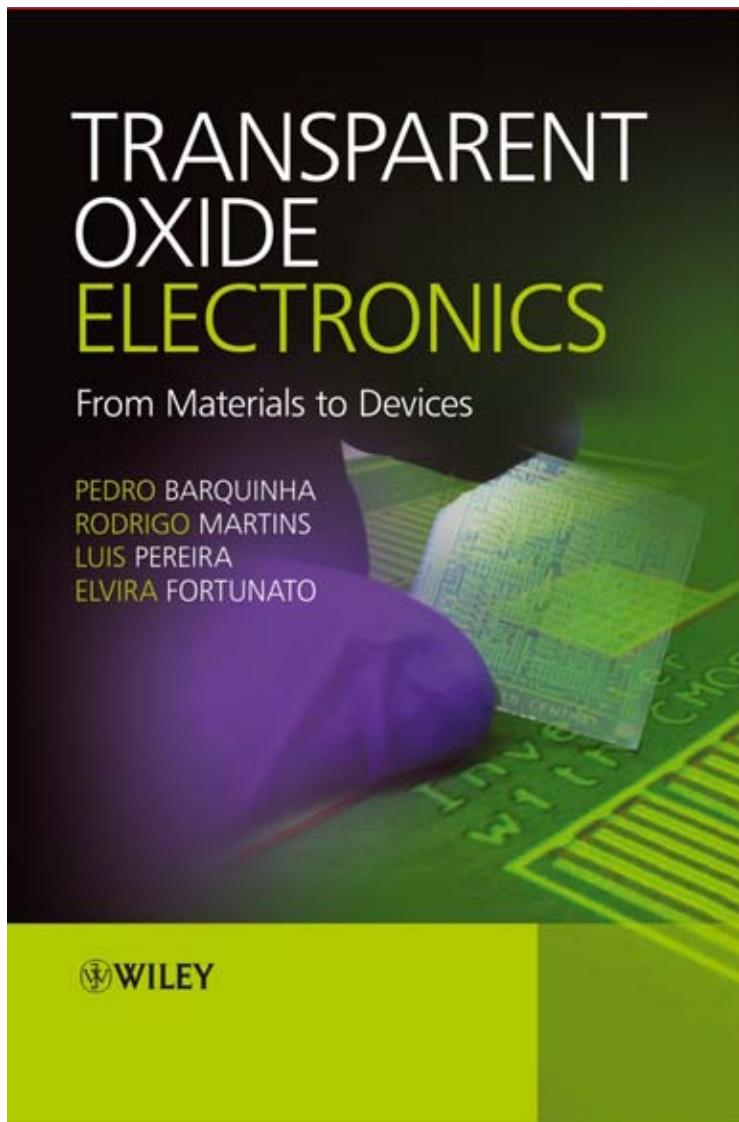
Received January 16, 2013; accepted March 7, 2013; published online March 27, 2013



The highest efficiency of **5.38%** was obtained in an Al-doped ZnO/nondoped Ga₂O₃/Cu₂O heterojunction solar cell.



Further reading...



2012

- N-type TOS
- P-type TOS
- Gate dielectrics in oxide electronics
- The (r)evolution of TFTs
- Electronics with and on paper
- Current and upcoming applications



“INVISIBLE”
(ERC-2008-AdG 228144)



Fundação para a Ciência e a Tecnologia
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Thank you for your attention!

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PHOTOPTICS 2014

2nd International Conference on Photonics, Optics and Laser Technology

